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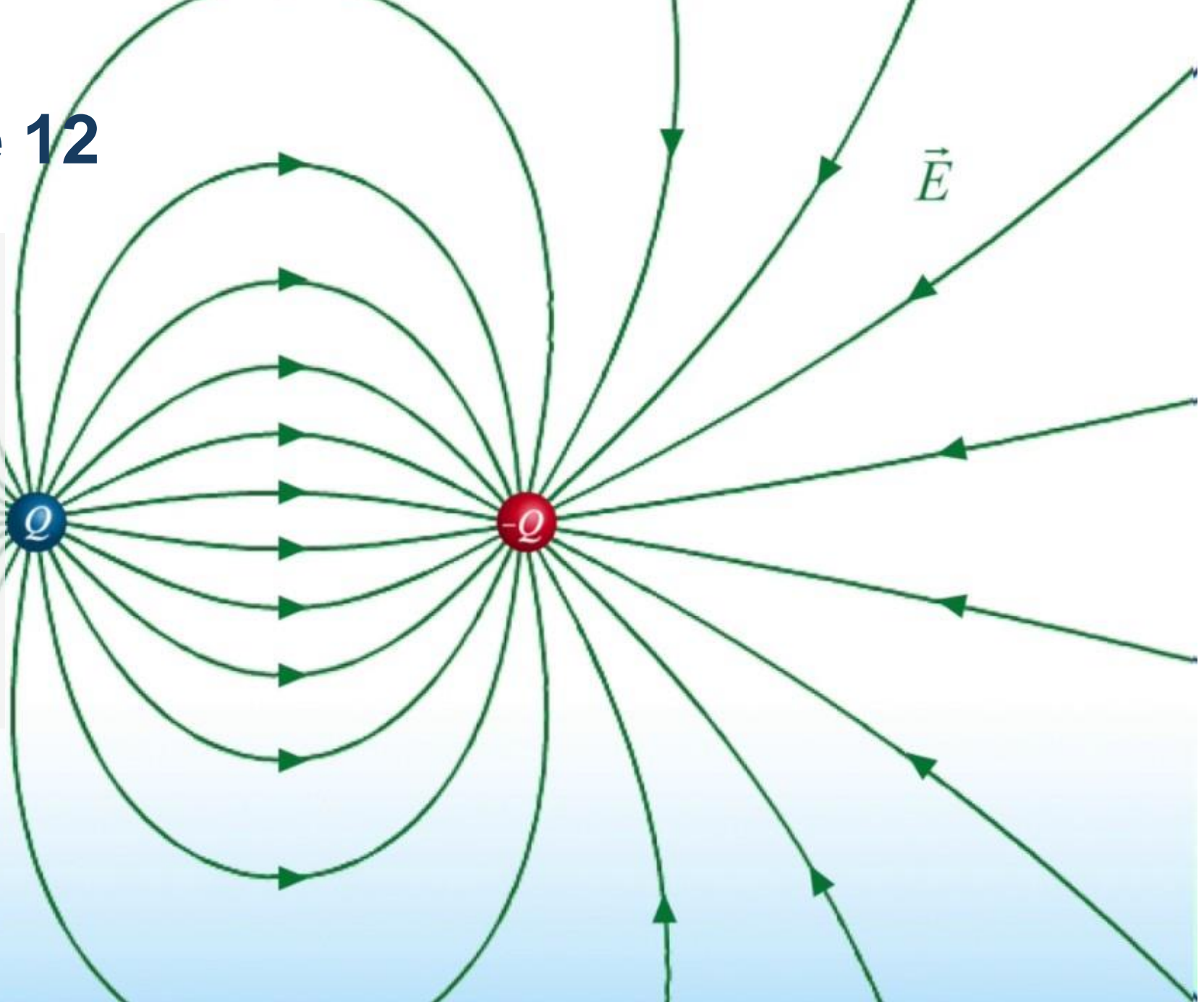
EITP25 2020

Lecture 12 – Ferroelectric Memories

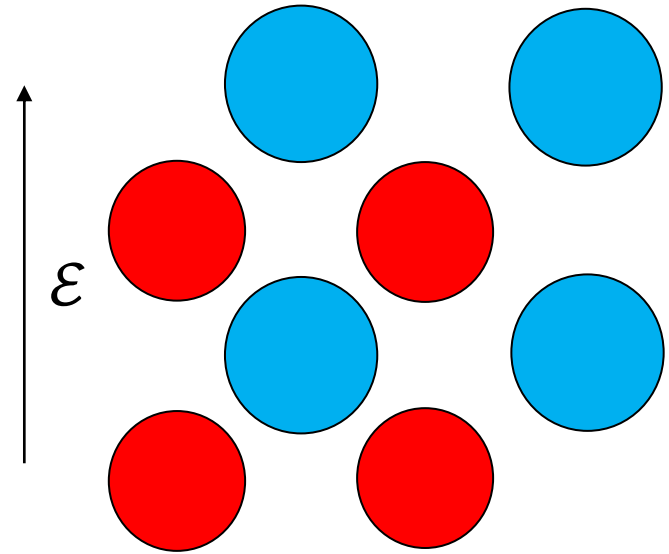
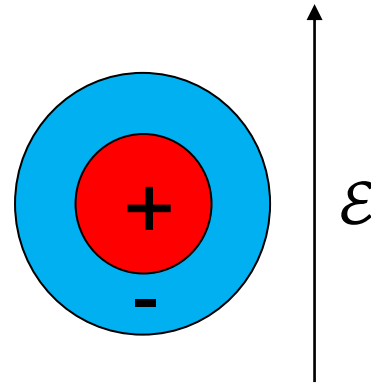
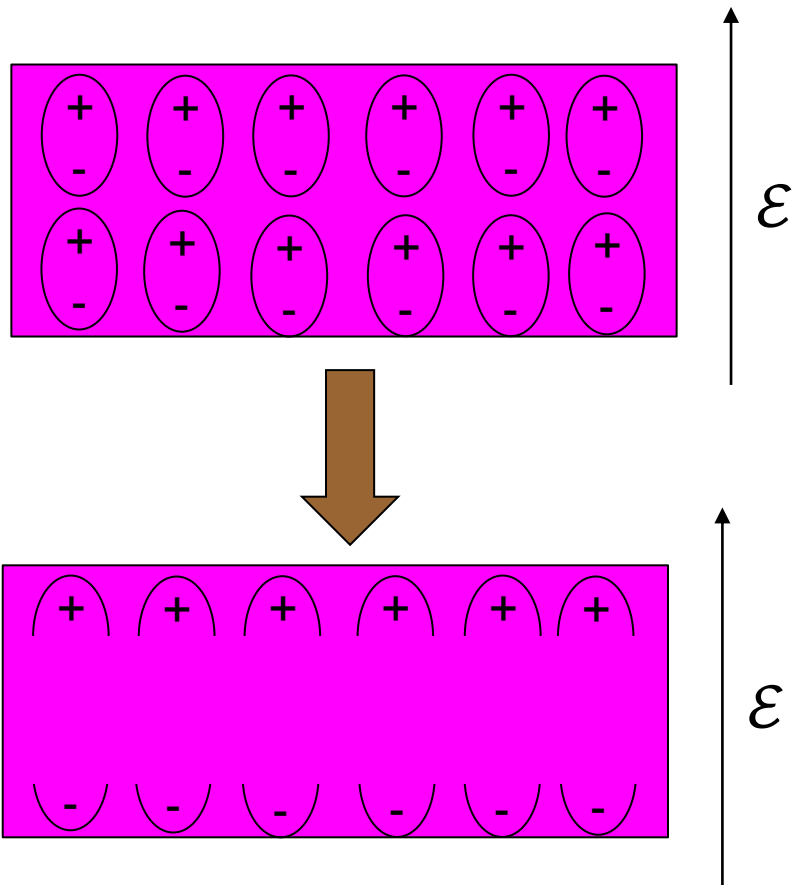


Outline – Lecture 12

- Ferroelectricity and Polarization
- Ferroelectric materials
- Three device types
 - FeRAM
 - FeFET
 - FTJ
- Ferro for neuromorphic
 - FeFET synapses
 - FTJ synapses



Polarization



$$P = \epsilon_0 \chi \mathcal{E}$$

$$D = \epsilon_0 \mathcal{E} + P$$

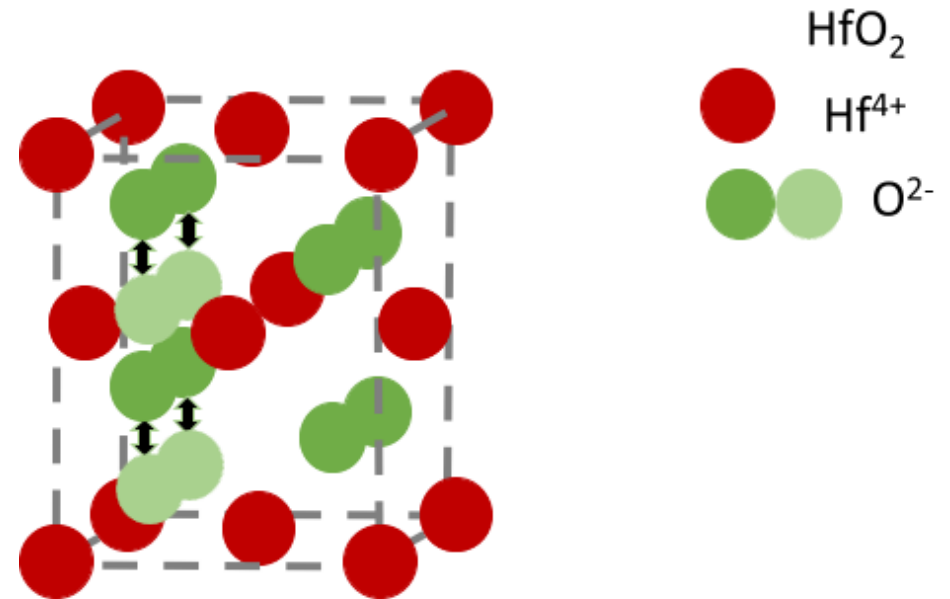
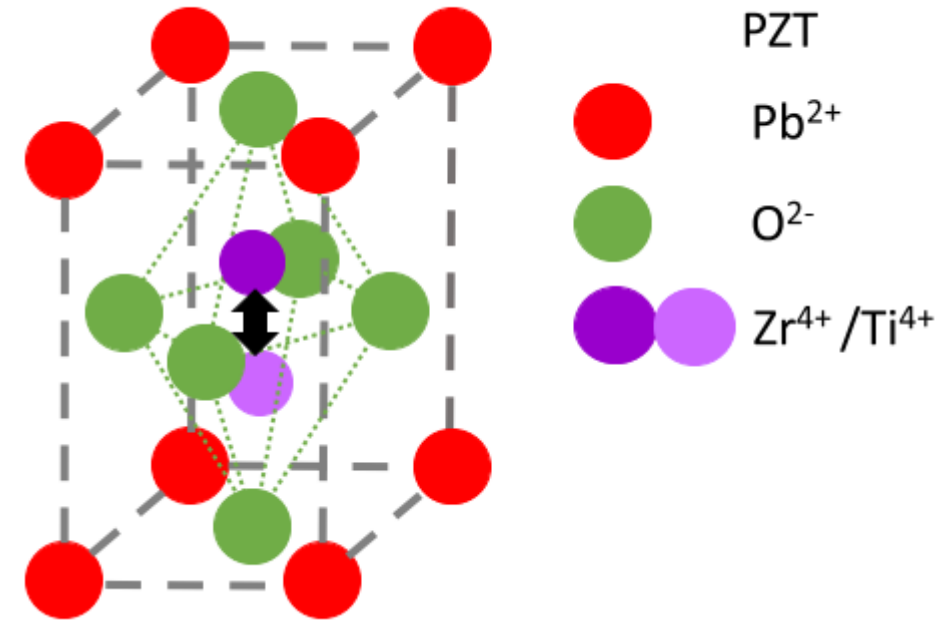
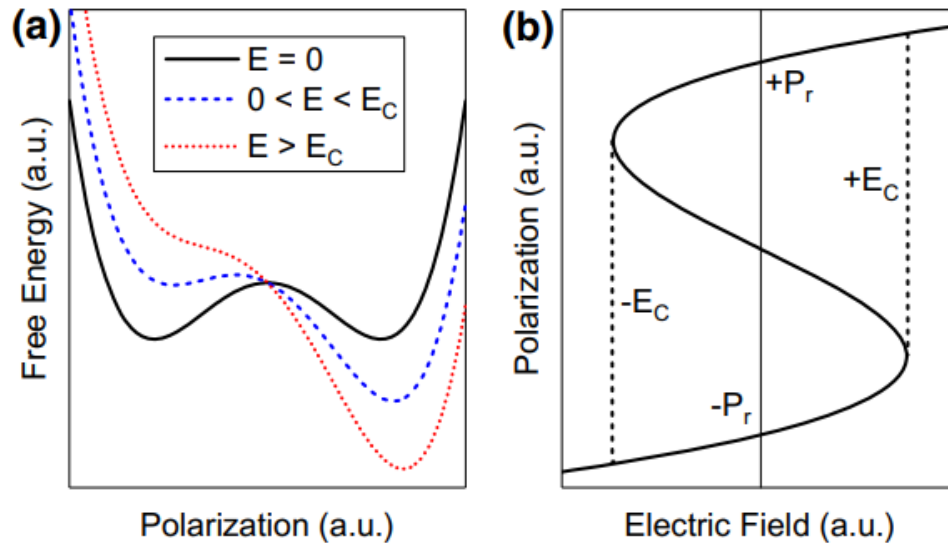
$$\rightarrow \epsilon_r = 1 + \chi$$

Ferroelectric polarization

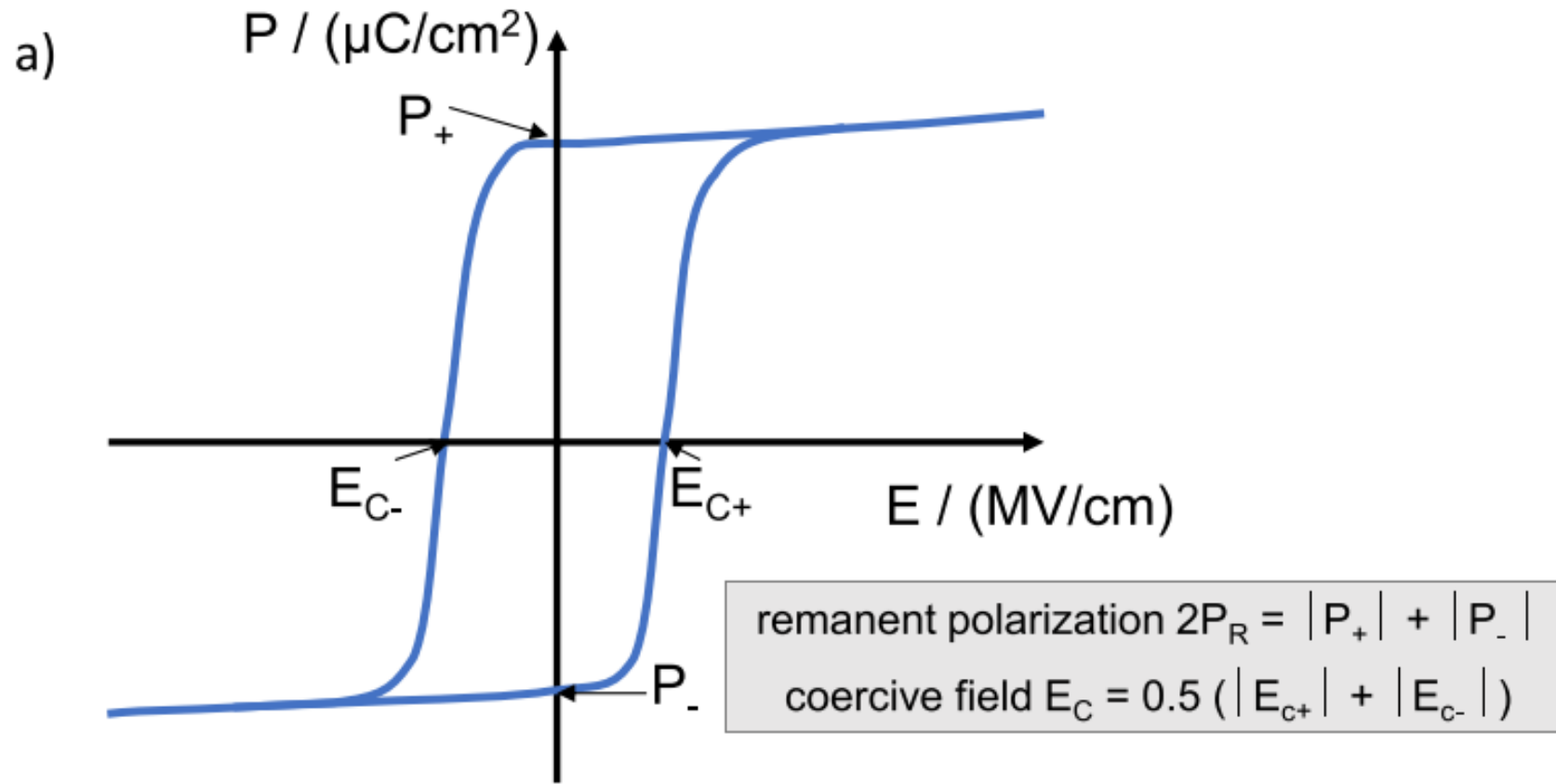
- Ferroelectricity: Polarisation remains even **without** externally applied electric field
- Requires non-centrosymmetric crystal structure
→ two polar equilibrium states

Free energy vs Polarization

$$U = \alpha P^2 + \beta P^4 - \varepsilon P, \quad \alpha < 0, \beta > 0$$



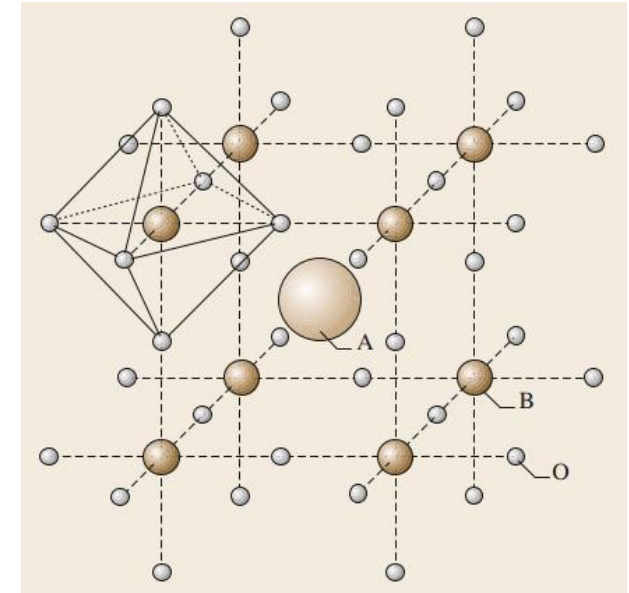
Polarization – electric field curve



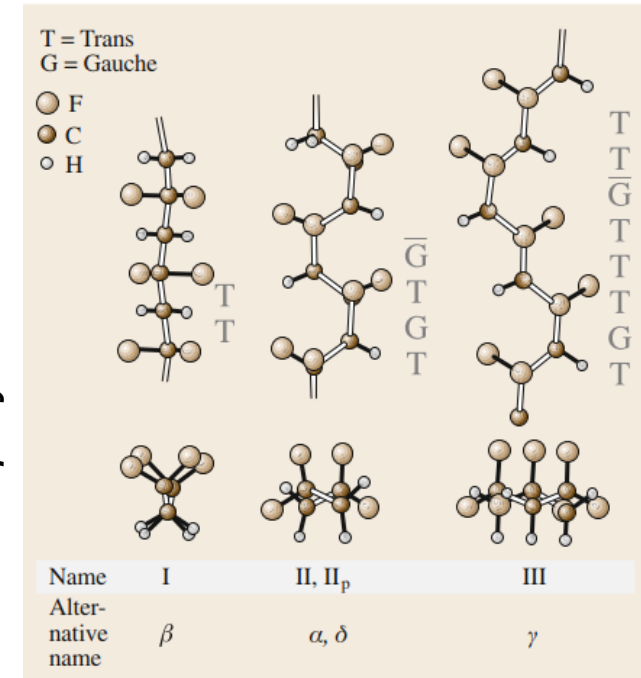
Ferroelectric materials

- Perovskite ferroelectrics
 - Distorted structures → ferroelectricity
 - BaTiO_3 , PbTiO_3 , KNbO_3 , **$\text{Pb}(\text{Zr}, \text{Ti})\text{O}_3$ (PZT)**...
 - Very high $\epsilon_r \sim 100 - 1000!!$
- Polyvinylidene fluoride (PVDF)
 - Polar bonds perpendicular to polymer chain aligns
 - $P_r \sim 13 \mu\text{C}/\text{cm}^2$
 - Flexible material
- Hafnium dioxed, HfO_2
 - FE effect discovered as late as in 2011!
 - Doping/stress → ferroelectricity
 - P_r 20-30 $\mu\text{C}/\text{cm}^2$
 - Ferroelectric at least down to 1 nm thickness
 - CMOS compatible

Perovskite crystal (CaTiO_3)

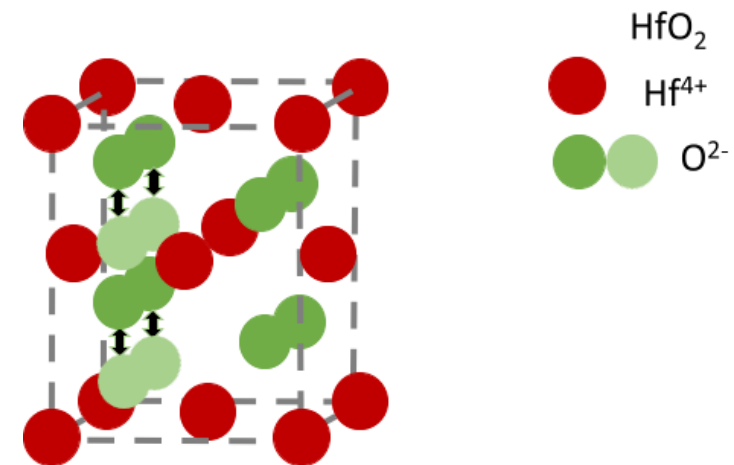
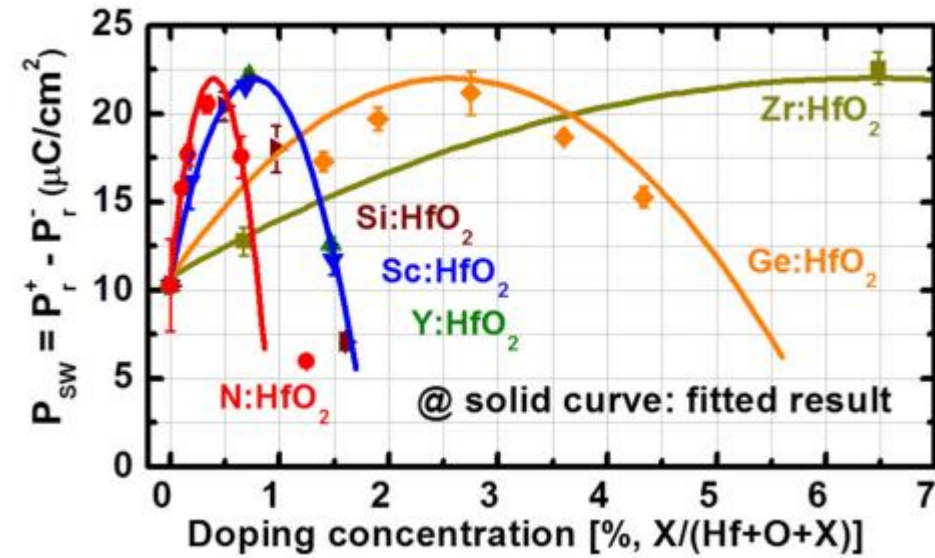


PVDF polymer chains



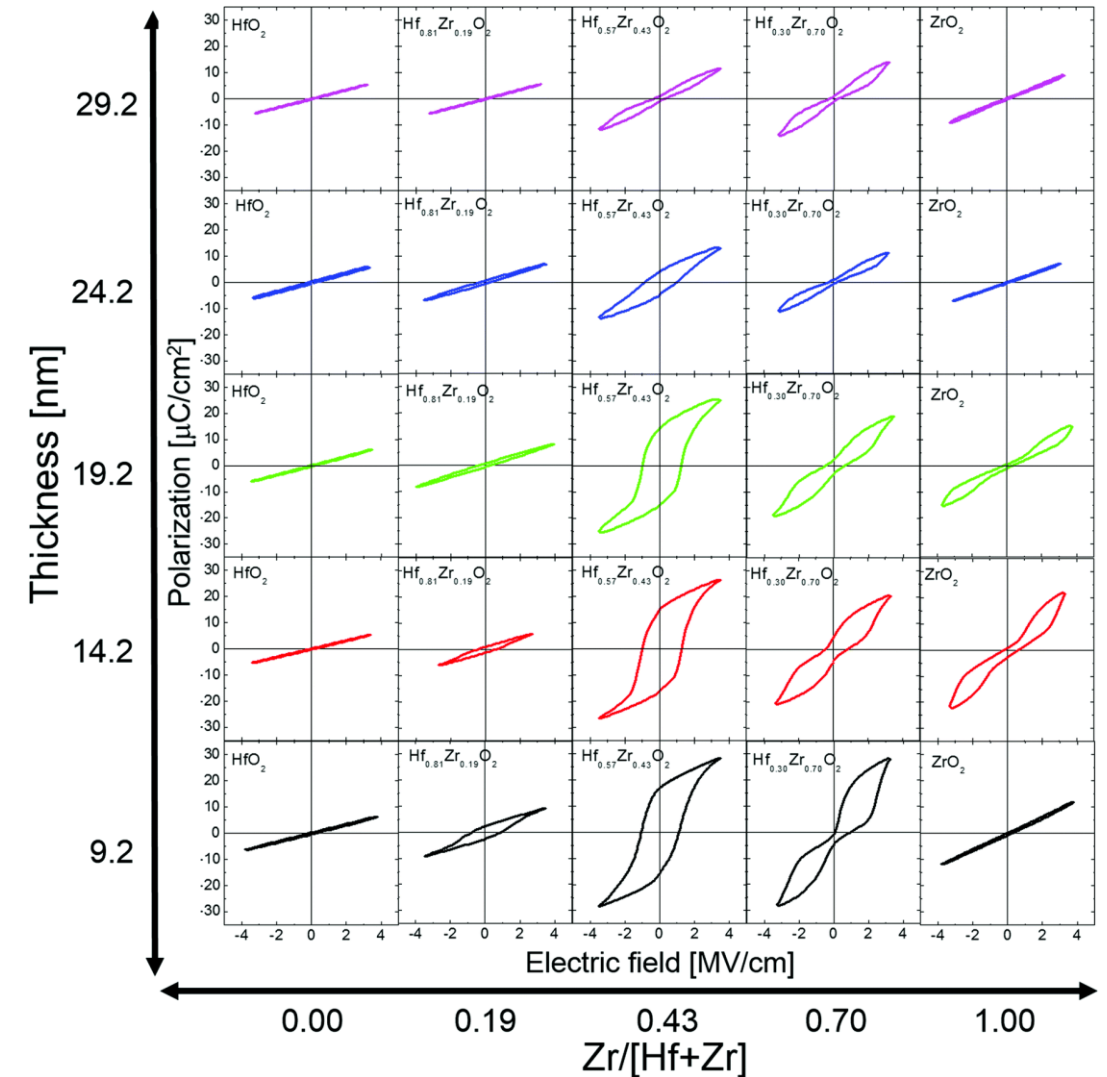
Ferroelectricity in doped HfO_2

- HfO_2 dopants: Si, Al, Y, Gd, La, Zr, ...
- Crystallization during thermal annealing
- Strain induces phase transition
 - Rhombohedral ferroelectric phase
 - O atoms switch place
- $\text{Hf}_{1-x}\text{Zr}_x\text{O}_2$ has become the most successful material



HfZrO₂ (HZO)

- P_r high for wide range of Zr content ($\text{Hf}_{1-x}\text{Zr}_x\text{O}_2$)
 - Maximum around $x = 50\%$
- Antiferroelectric at higher Zr-content.
- Thinner films (< 15 nm) yield higher P_r .
- Related to fraction of phases:
 - **Monoclinic m-phase:** paraelectric
 - Most stable at large thicknesses
 - **Orthorhombic o-phase:** ferroelectric
 - **Tetragonal t-phase:** antiferroelectric
 - Most stable in ZrO₂



Exercise: High coercive field in HZO

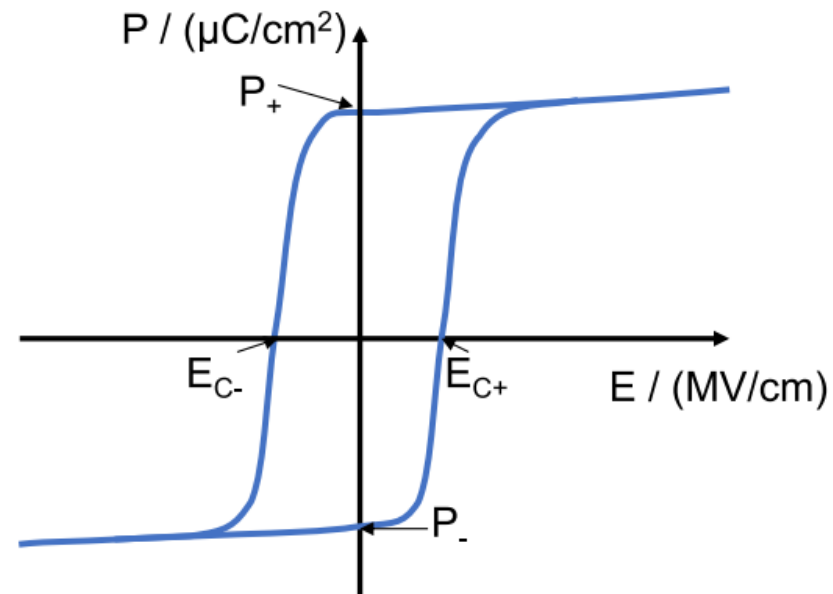
The higher E_c allows for scaling down the thickness.

1. Why is that?

2. Why is this important from a technological point of view?

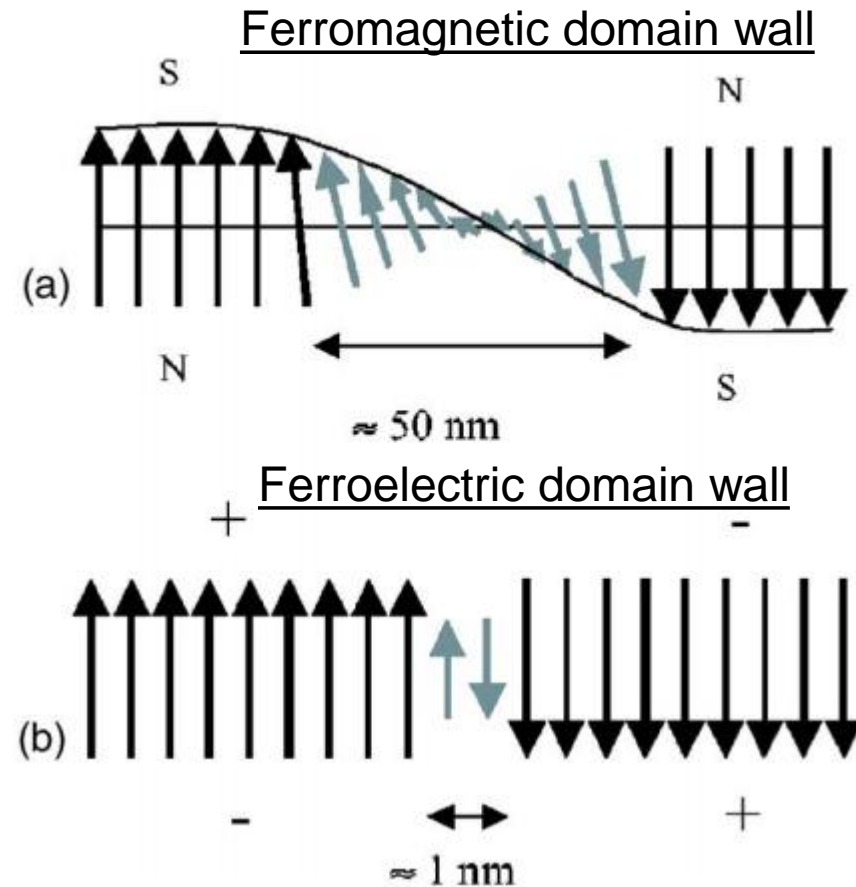
Coercive field comparison

Material	E_c (MV/m)
PVDF	1
LiTaO ₃	1.7
LiNbO ₃	4
PbZrTiO ₃	10
HfZrO ₃	150-200(!!)

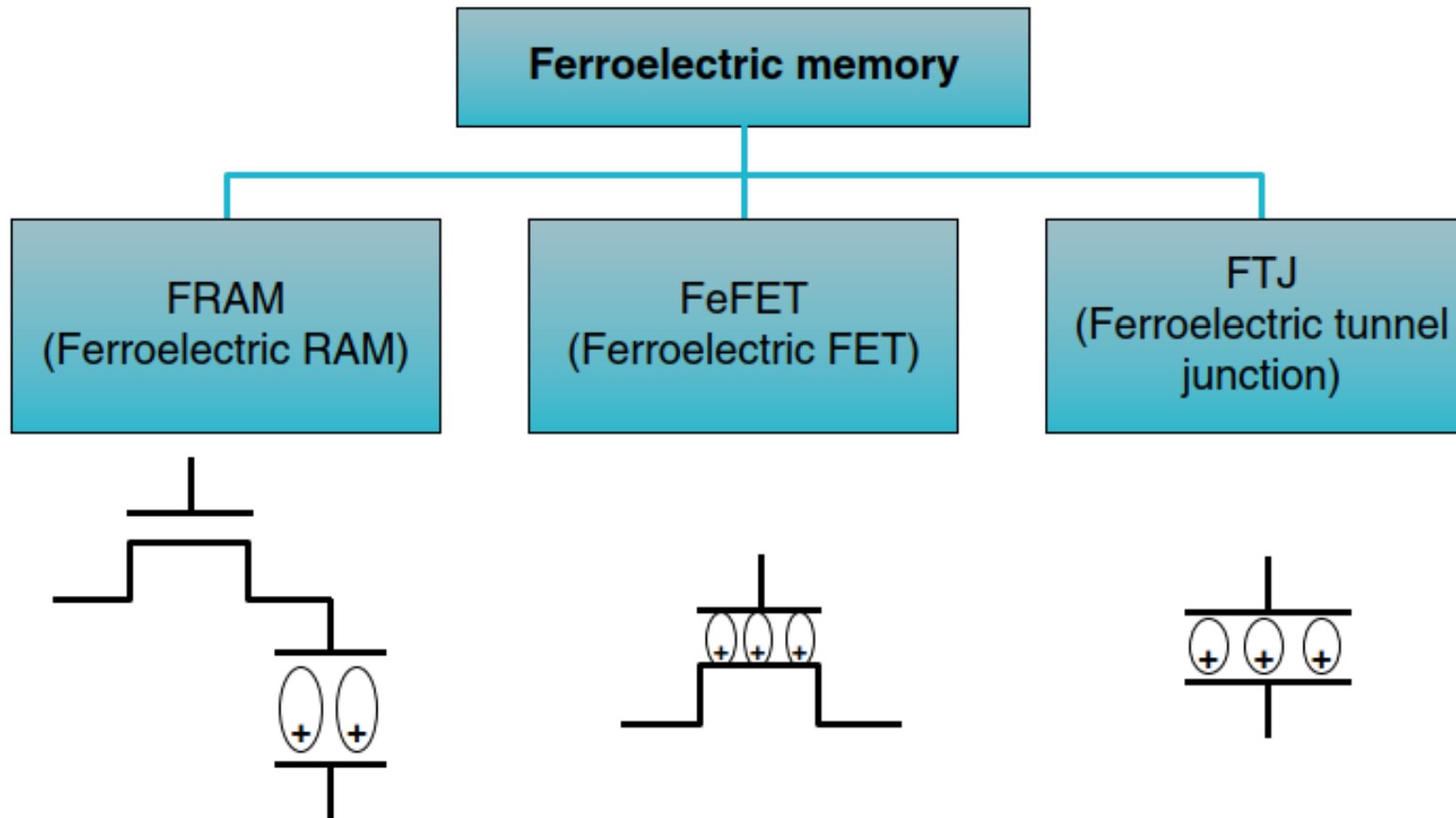


Scalability of ferroelectric memories

- Ferroelectricity scales better than ferromagnetism!
- Scaling limited by minimum size of a stable FE domain
- At least retains ferroelectricity below 10 nm diameter.
- HZO retains FE down to 1 nm thickness (at least!)

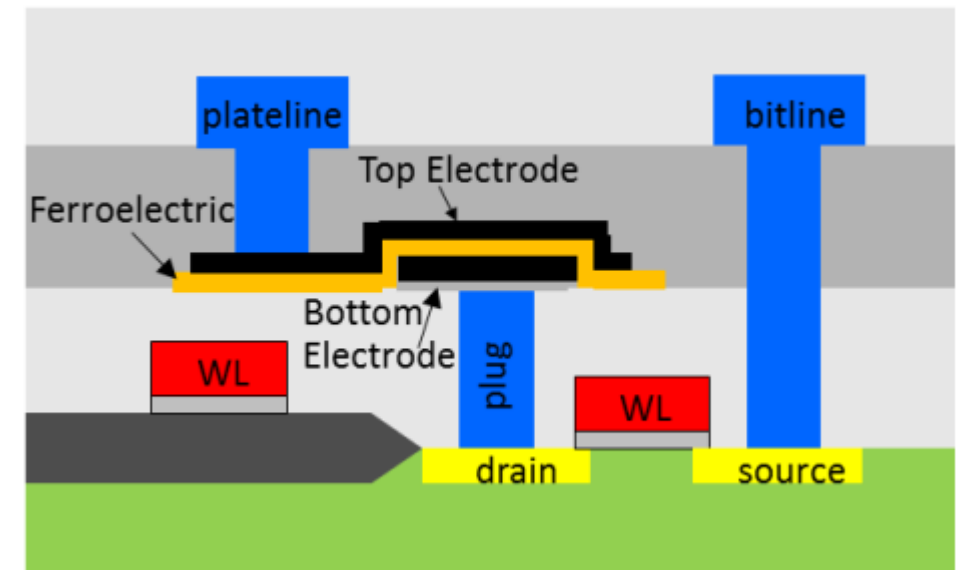


Three types of memory types



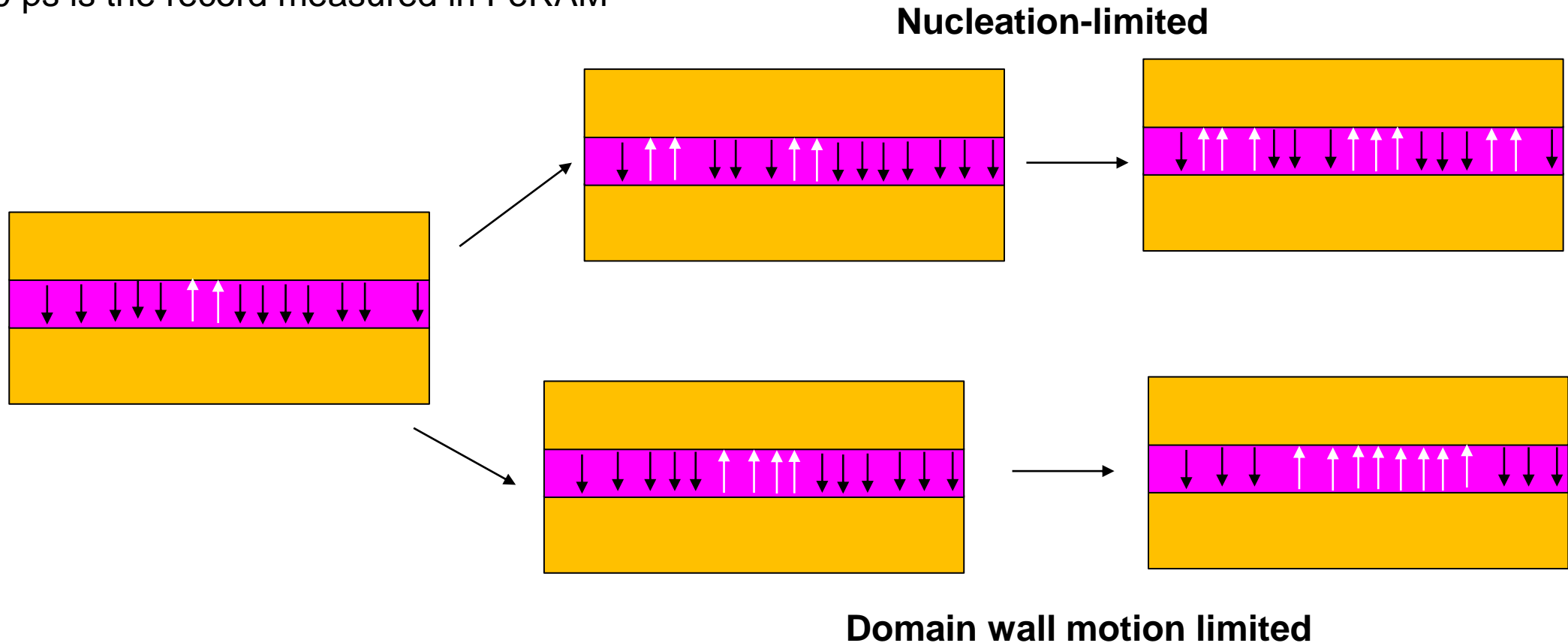
FeRAM

- Ferroelectric capacitor placed in series with MOSFET selector.
 - Structure is identical to DRAM, but non-volatile!
- Ferroelectric state is sensed by applying switching voltage and see whether it switches or not
- Destructive read
- Limited scalability due to needed size for sizeable capacitive current – 90 nm
- Endurance demonstrated up to 10^{12} cycles!
- Commercially available
 - 32 kbit Fujitsu FRAM in PS2



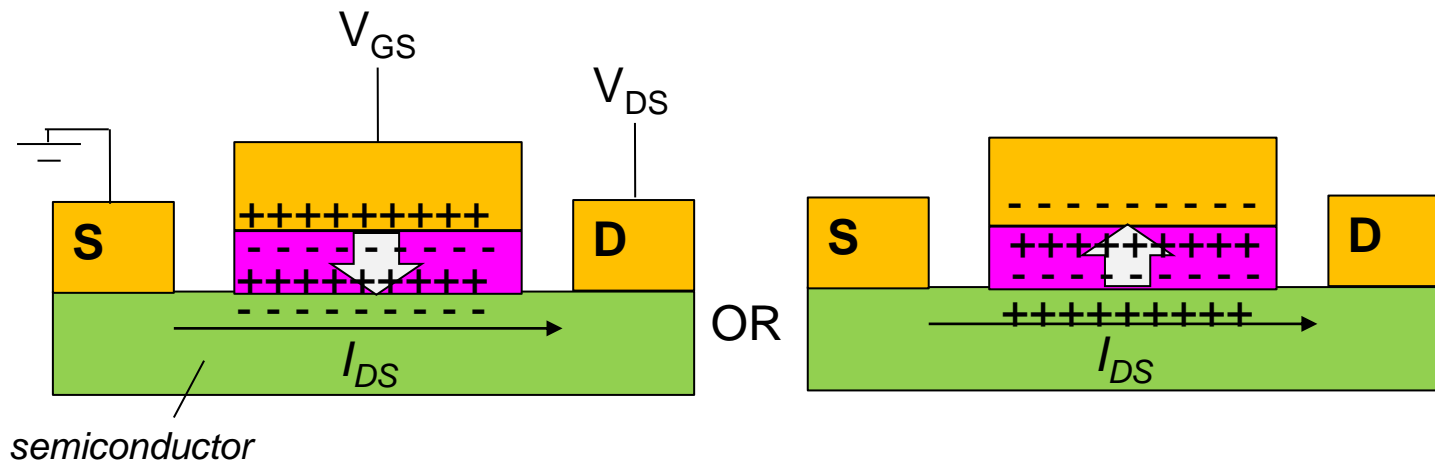
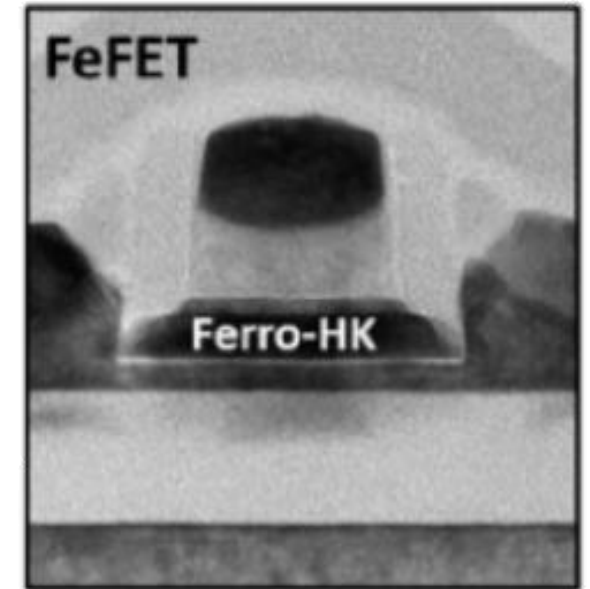
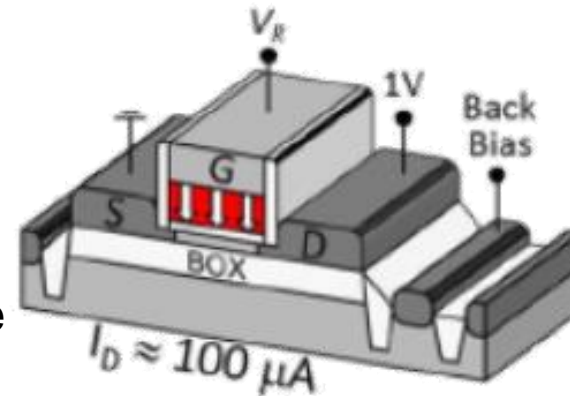
Switch speed

- Speed is limited by generation of new reverse ferroelectric domains, nucleation rather than domain motion < 1 ns
- 280 ps is the record measured in FeRAM



FeFET

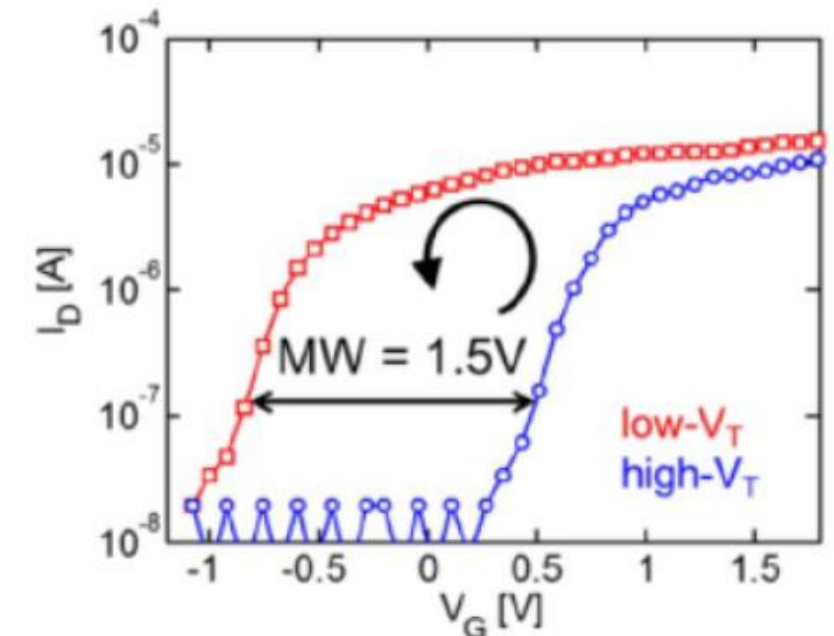
- Integrate ferroelectric gate dielectric in MOSFET
- Polarization state shifts MOSFET threshold voltage



semiconductor

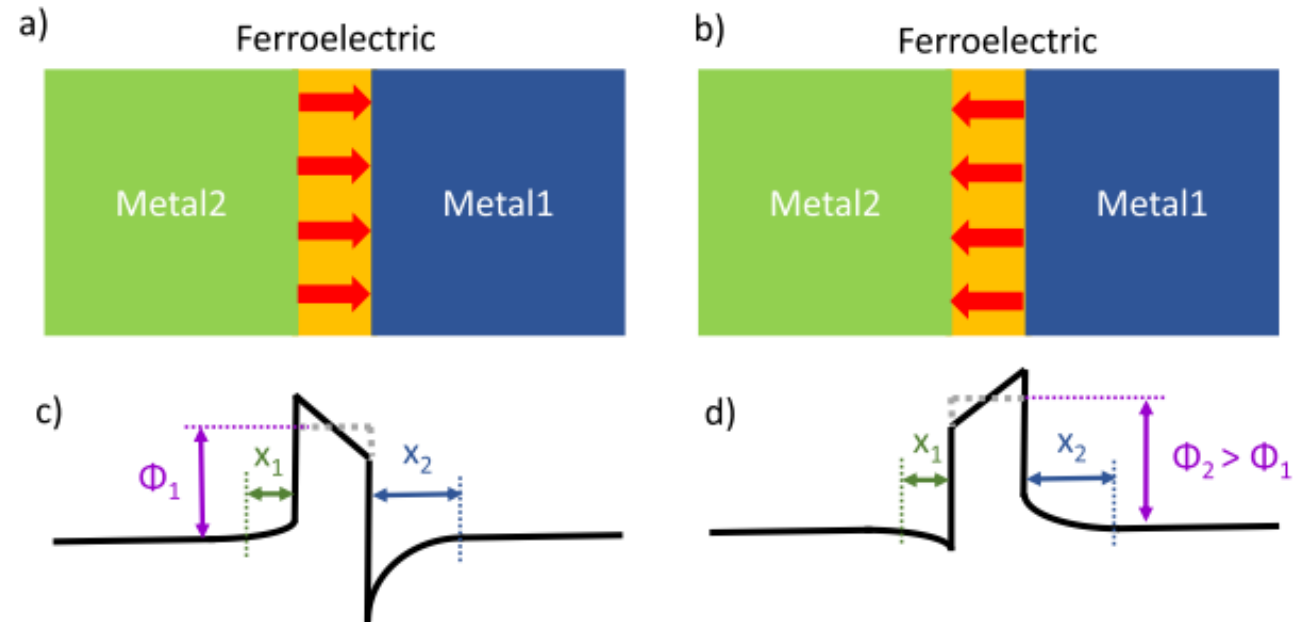
Three main challenges:

1. Control the interface in metal-FE-semiconductor system
2. Realizing 10 year retention
3. Realizing high endurance



Ferroelectric Tunnel junction

- Two-terminal resistive memory
- Relies on transport through the ferroelectric layer
- Contacts have different anisotropy in screening length
→ different electronic band bending
- Leakage current depends on the polarization state → $R_{\text{off}}/R_{\text{on}}$ contrast



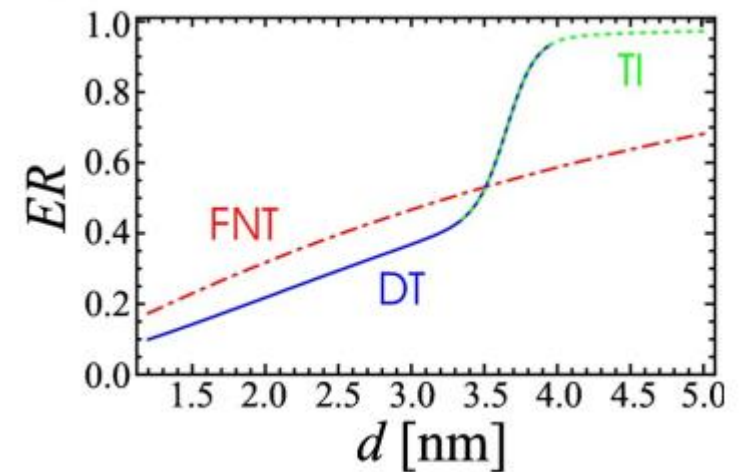
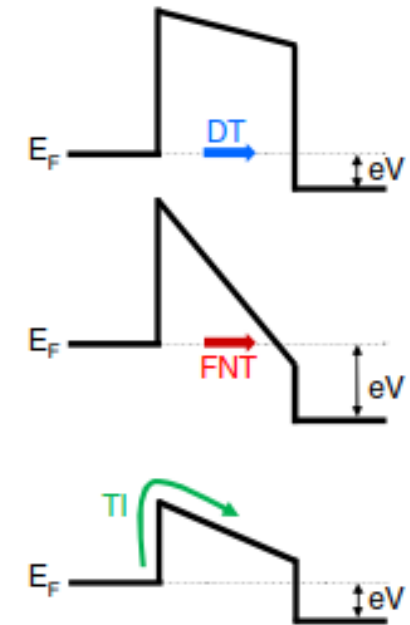
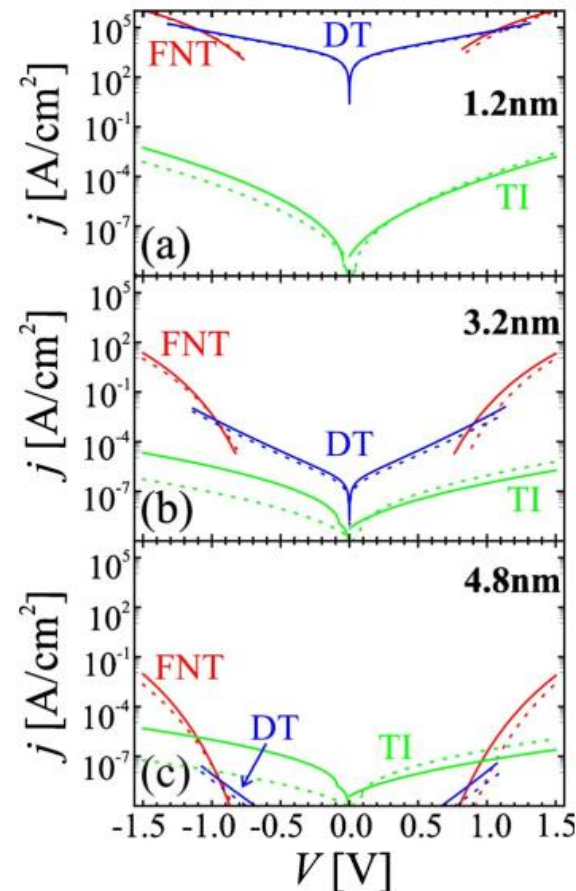
Transport in metal-FE-metal FTJs

- Like in ReRAM, many transport paths, not all affected by FE
- For maximum $R_{\text{off}}/R_{\text{on}}$:

- Thermionic Injection (TI)
- Direct tunneling (DT)
- Fowler-Nordheim Tunneling (FNT)
- Trap-assisted tunneling
- Electron hopping

→ Need thin enough layer for efficient TI
 → But not too thin! → DT, FNT

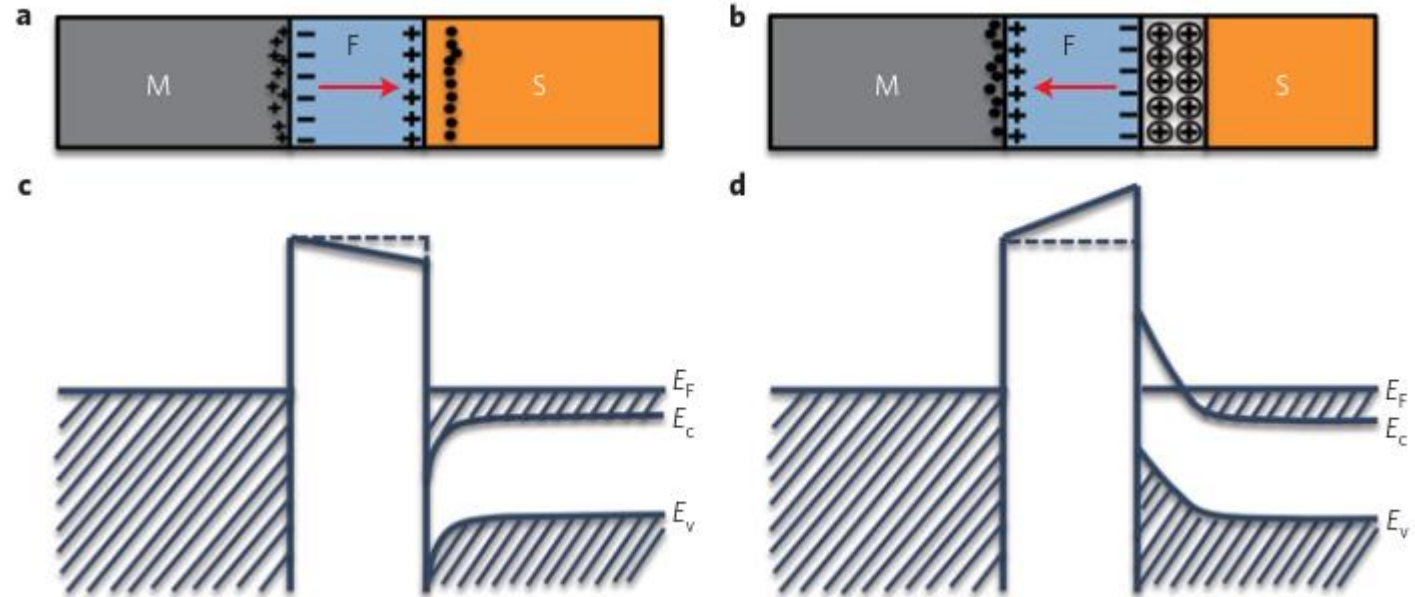
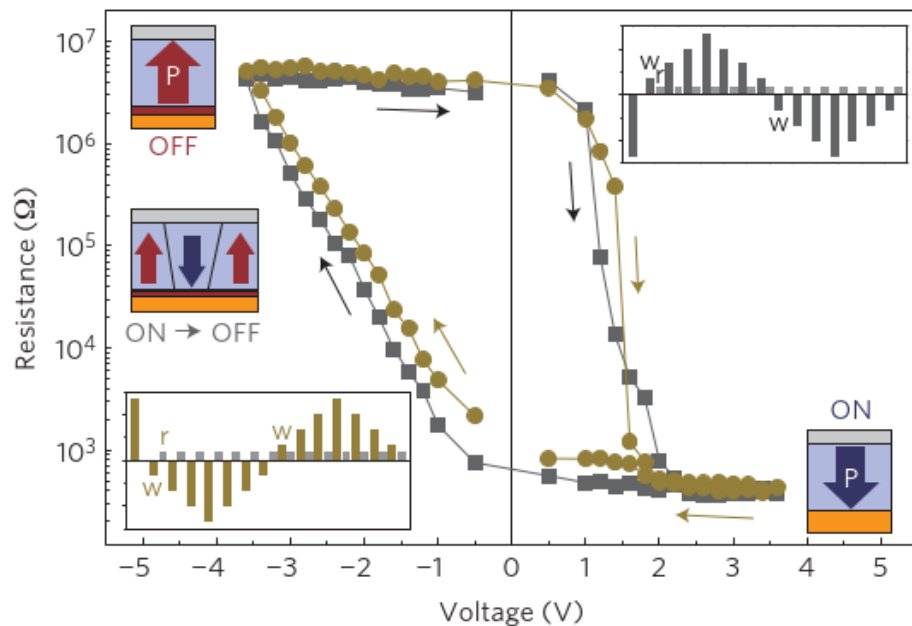
- Examples of TER > 1000



$$ER = \frac{j(P > 0) - j(P < 0)}{j_>}$$

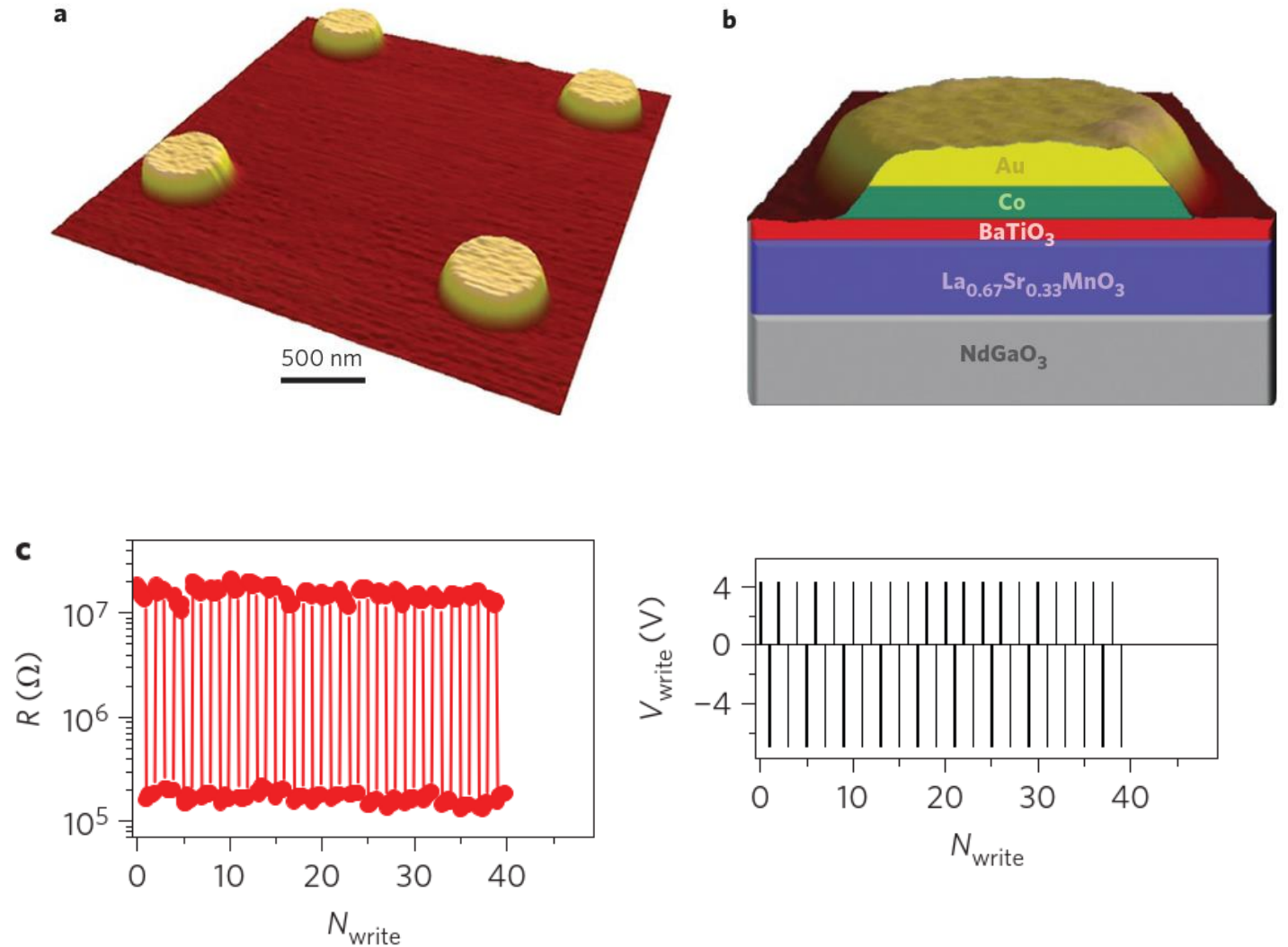
Metal-FE-semiconductor FTJs

- Semiconductors can be depleted \rightarrow Modulation of tunnel barrier **width**!
- Large R contrast even with direct tunneling
- TER $> 10^6$ achieved



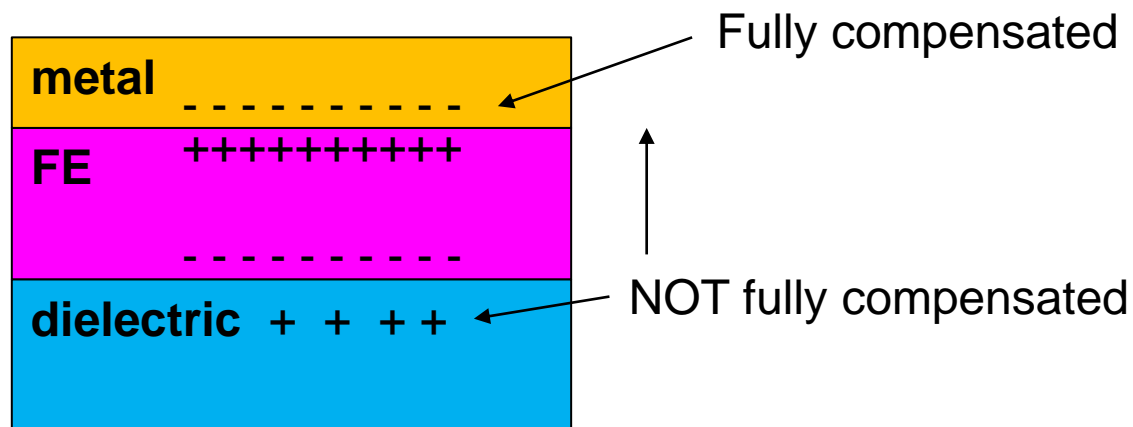
Energy consumption FTJs

- 200 nm devices contacted by conductive AFM
- $t_{\text{write}} = 10 \text{ ns}$ write pulses at 4 V.
 $\rightarrow E = t_{\text{write}} * V_{\text{write}} * I = 130 \text{ fJ}$
- For 50 nm devices $\rightarrow E \sim 10 \text{ fJ/bit}$
- Why?
 - Purely electrostatic writing
 - No filament formation
 - No phase change
 - Not current-induced (like STT)



Retention in FE memories - Depolarization field

- If the surface surrounding the ferroelectric material cannot supply the charge to completely compensate the polarization charge → depolarization field
- Acts to depolarize → reduces retention
- Any interfacial layers will lead to a depolarization field

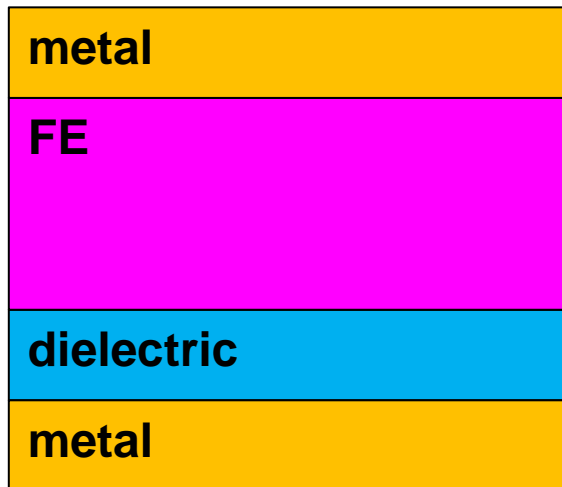


$$E_{dep} = -P \left[\epsilon_0 \epsilon_{FE} \left(\frac{C_{di}}{C_{FE}} + 1 \right) \right]^{-1}$$

- Want $C_{di} \gg C_{FE}$ to minimize depolarization field
→ $\epsilon_{di} \gg \epsilon_{FE}$, and $t_{di} \ll t_{FE}$

2 min exercise – Magnitude of depolarization?

- How big is this compared to the critical field ε_c of HZO (1.5 MV/cm)
- What will be the impact on retention?



$$t_{FE} = 10 \text{ nm}$$

$$\varepsilon_{FE} = 20$$

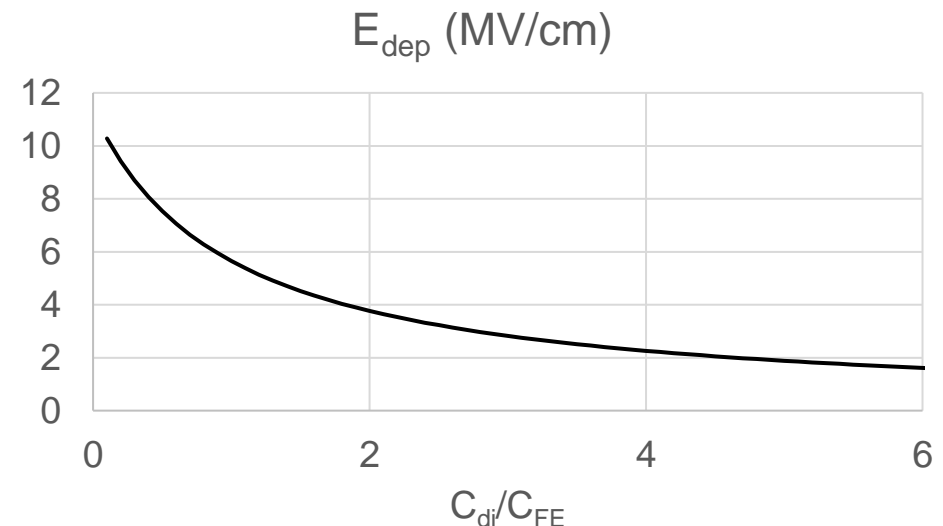
$$t_{di} = 1 \text{ nm}$$

$$\varepsilon_{di} = 10$$

$$E_{dep} = -P \left[\varepsilon_0 \varepsilon_{FE} \left(\frac{C_{di}}{C_{FE}} + 1 \right) \right]^{-1}$$

$$P = 20 \text{ } \mu\text{C}/\text{cm}^2$$

$$\varepsilon_0 = 8.83 * 10^{-14} \text{ F/cm}$$



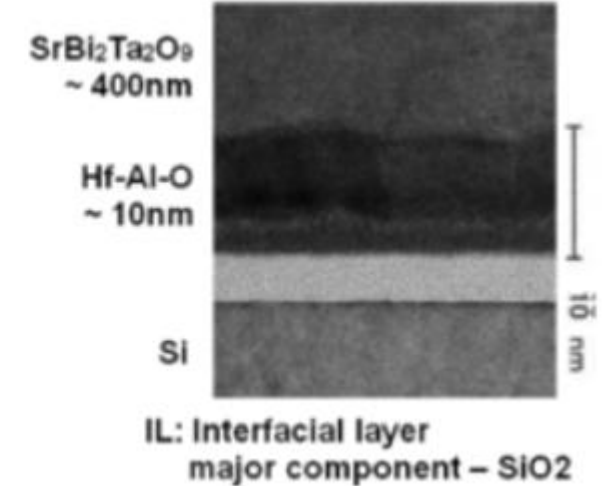
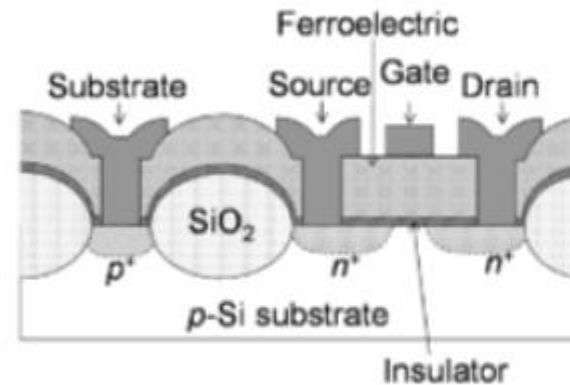
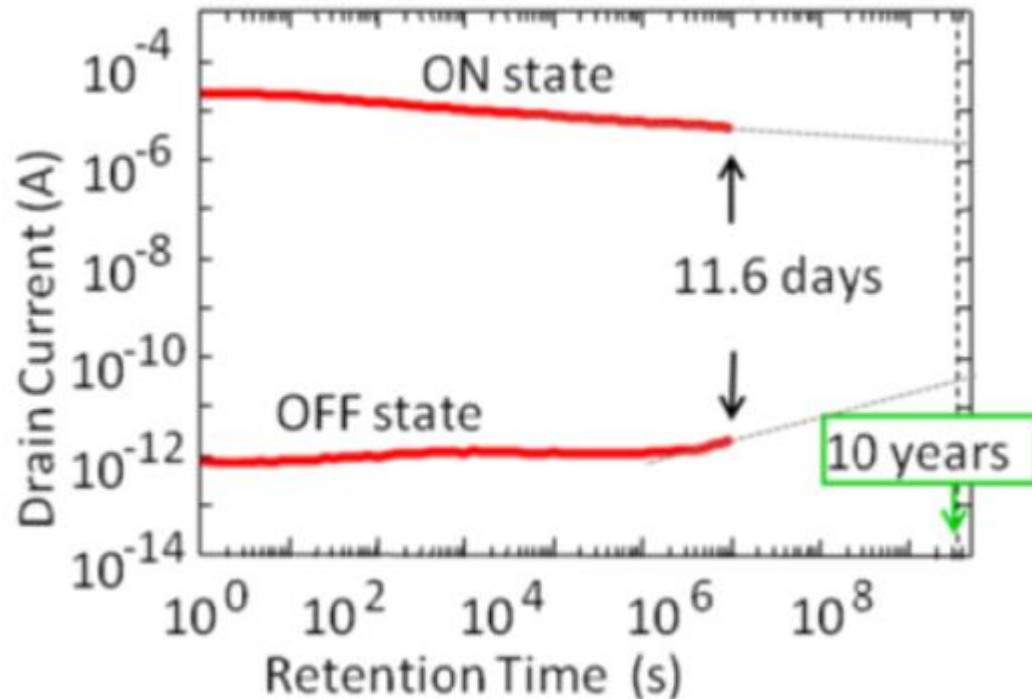
Achieving 10 year retention

- A matter of optimizing the layer stack, achieved in 2004
- 400 nm SBT + 10 nm HfAlO₂
- But not scalable! **WHY?**

$$\epsilon_{SBT} \sim 110,$$

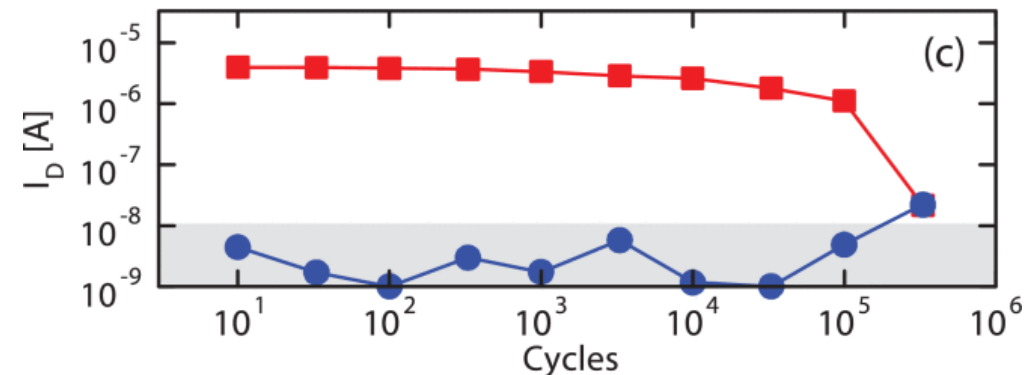
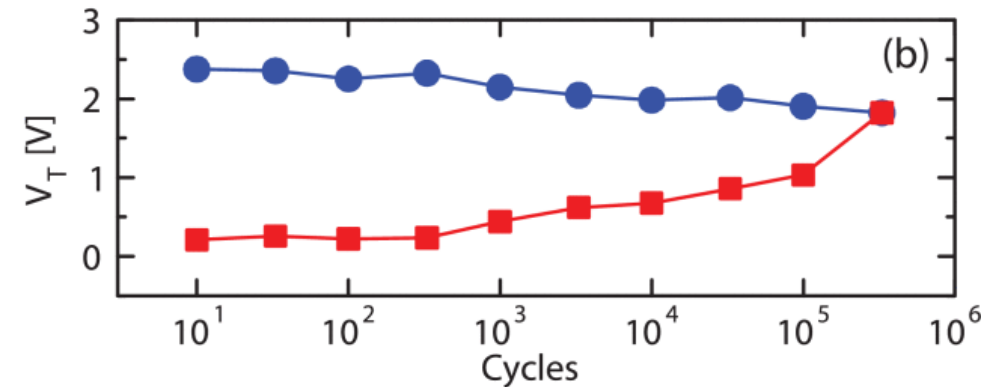
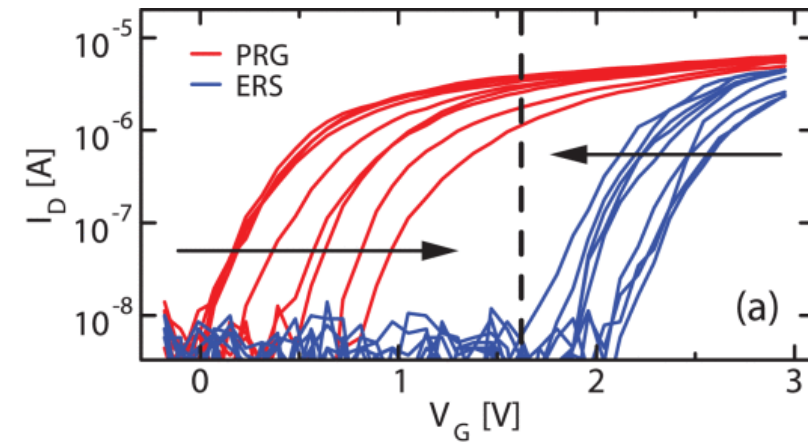
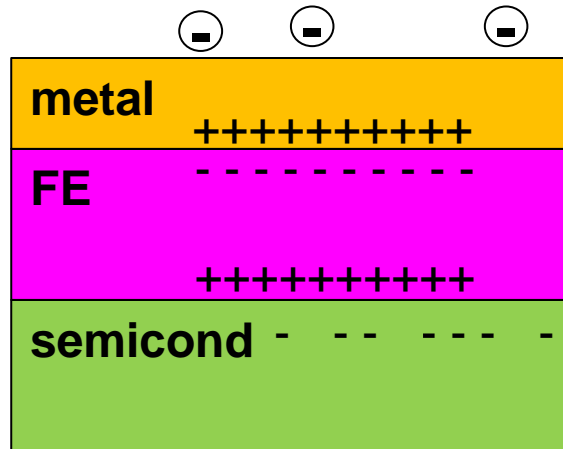
$$\epsilon_{HfAlO_2} \sim 11$$

$$\frac{C_{HAO}}{C_{SBT}} = \frac{\frac{11}{10 \text{ nm}}}{\frac{110}{400 \text{ nm}}} = 4$$



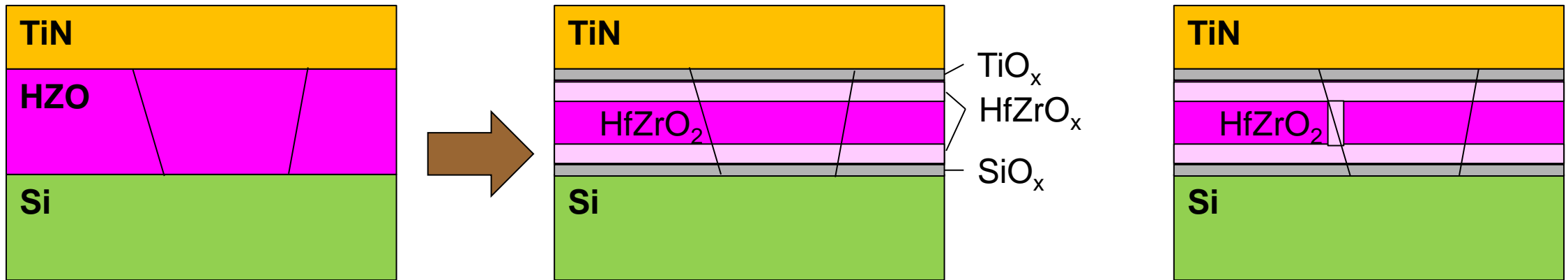
Endurance

- With each write cycle the memory window shrinks
- Due to high-voltage cycling
 - creation of additional charges in oxide (screening of P charge)
- Particularly difficult for FeFETs
 - devices demonstrated up to 10^5 cycles



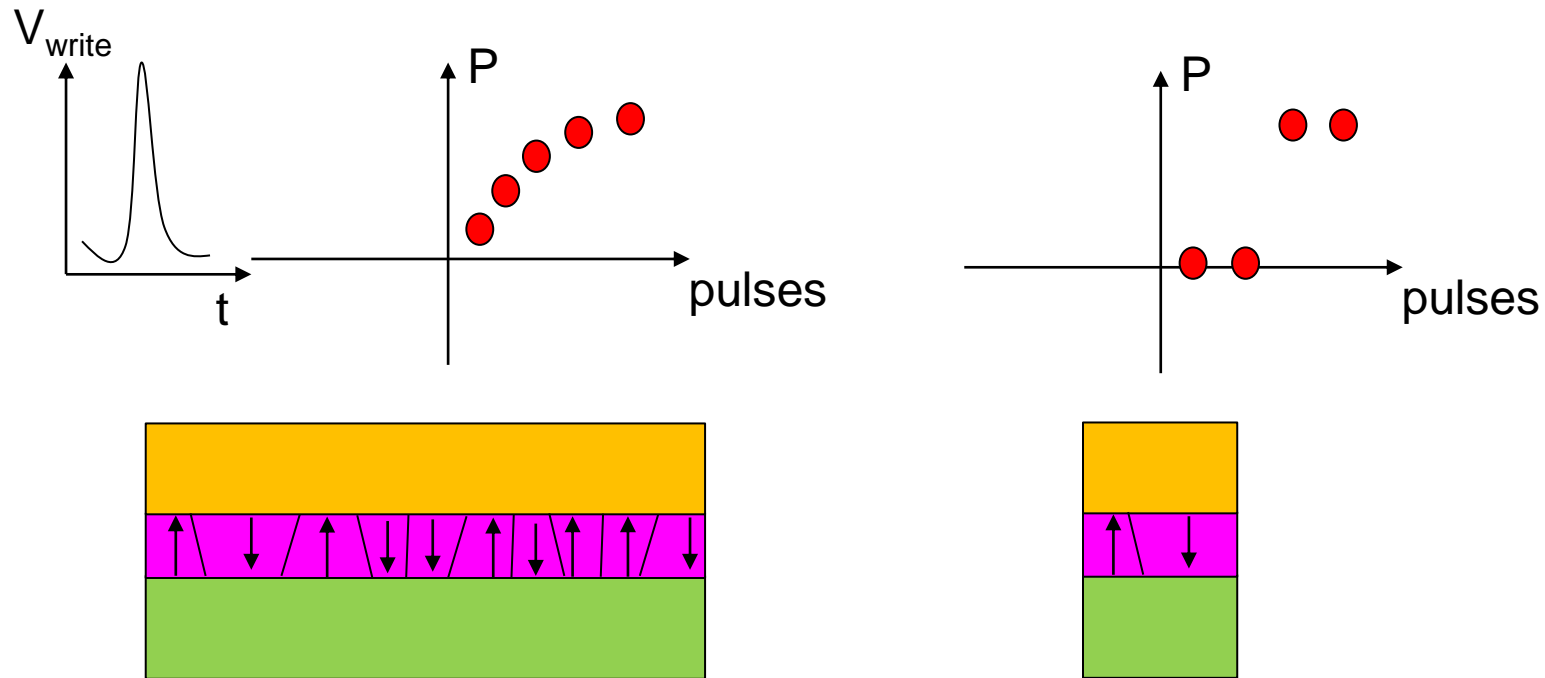
Cause of endurance failure

- The interface quality is vital!
- Diffusion across interfaces
- Non-switching low-k interface layers → voltage division
 - High voltage drop → more defects → layers continue to grow → less voltage over FE layer
 - Also: V_O formation/diffusion → ReRAM effect in grain boundaries! → BREAKDOWN!



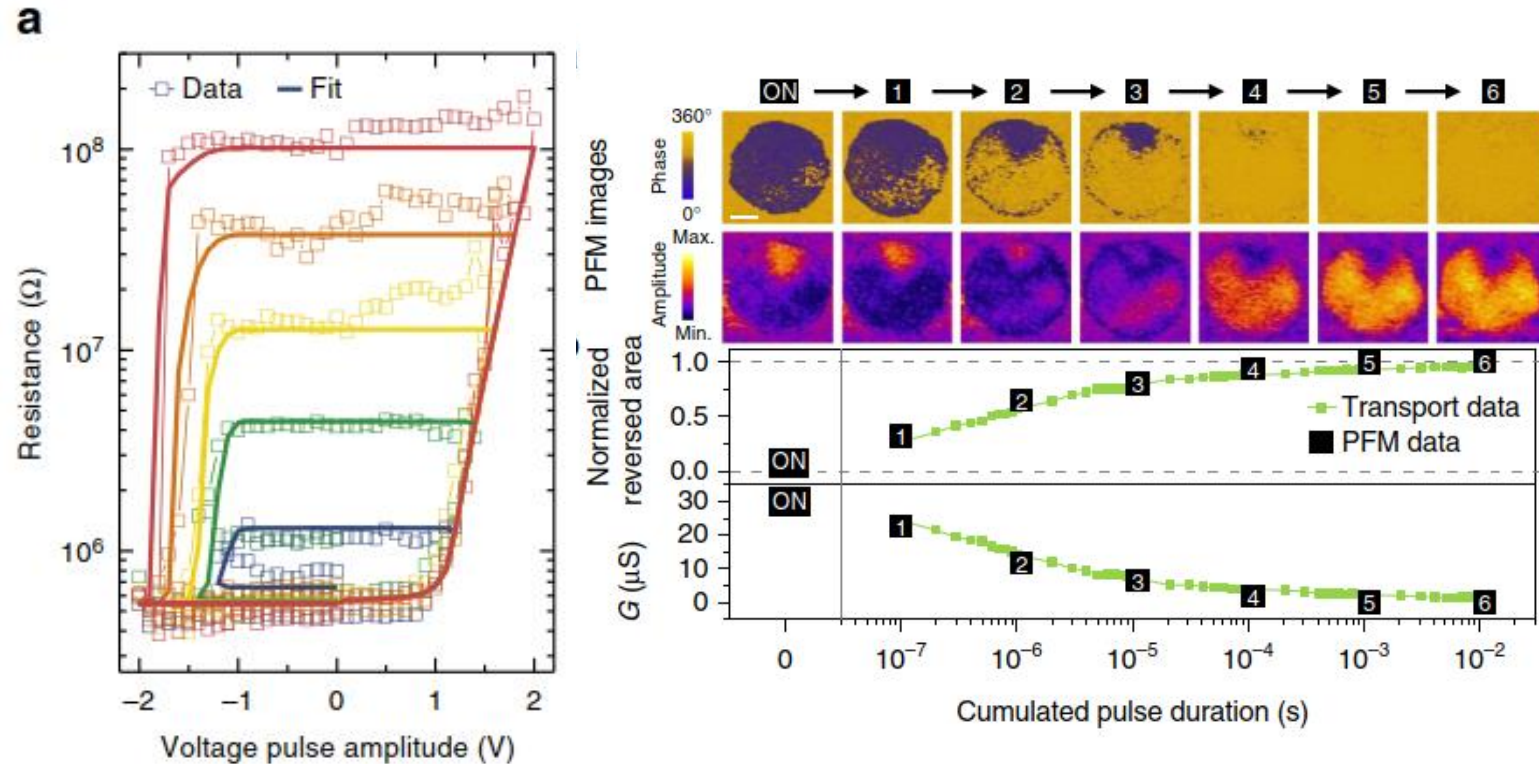
Multibit operation??

- Possible in large devices (multiple domains)
- Nanoscale devices (1-few domains) \rightarrow binary devices



Inhomogeneous FE switching

- BeFeO₃ ferroelectric
 - Domain size < 10 nm
- 150 nm diameter devices
 - Scaled but still lots of domains
- FE switching nucleation-dominated
 - New domains rather than extending
- Can enable memristor behavior in FTJs



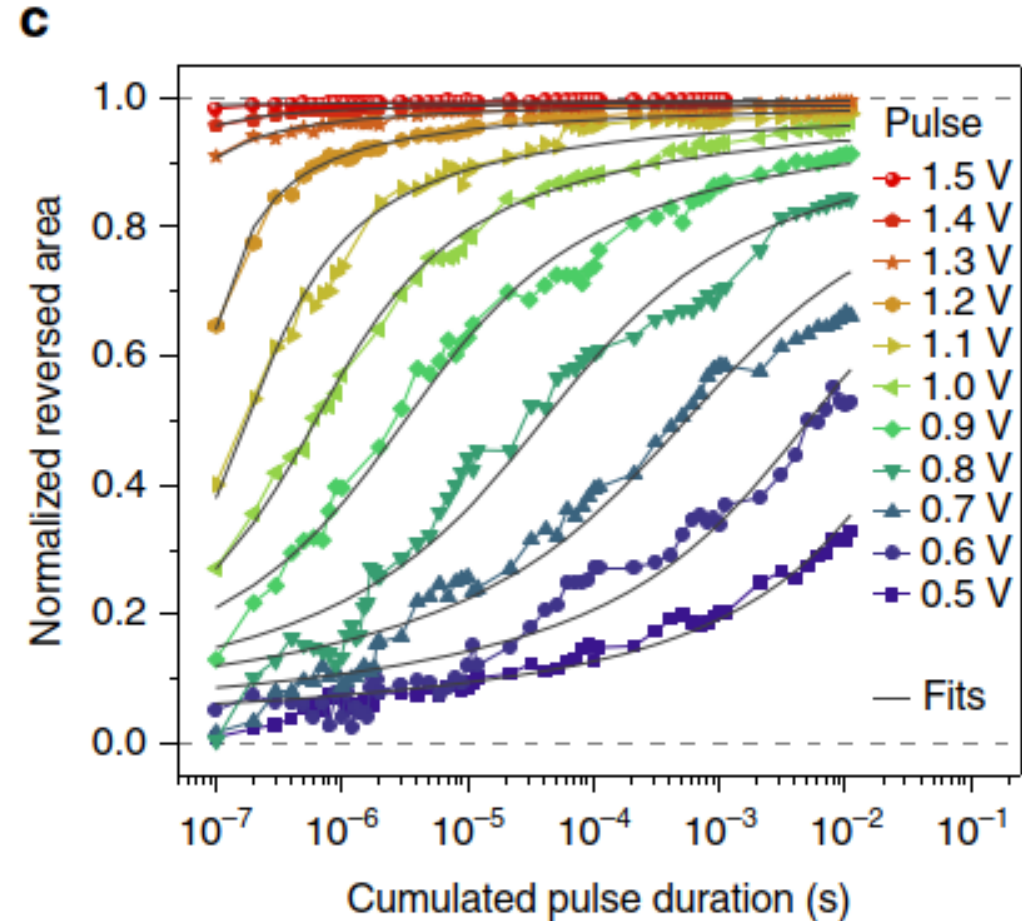
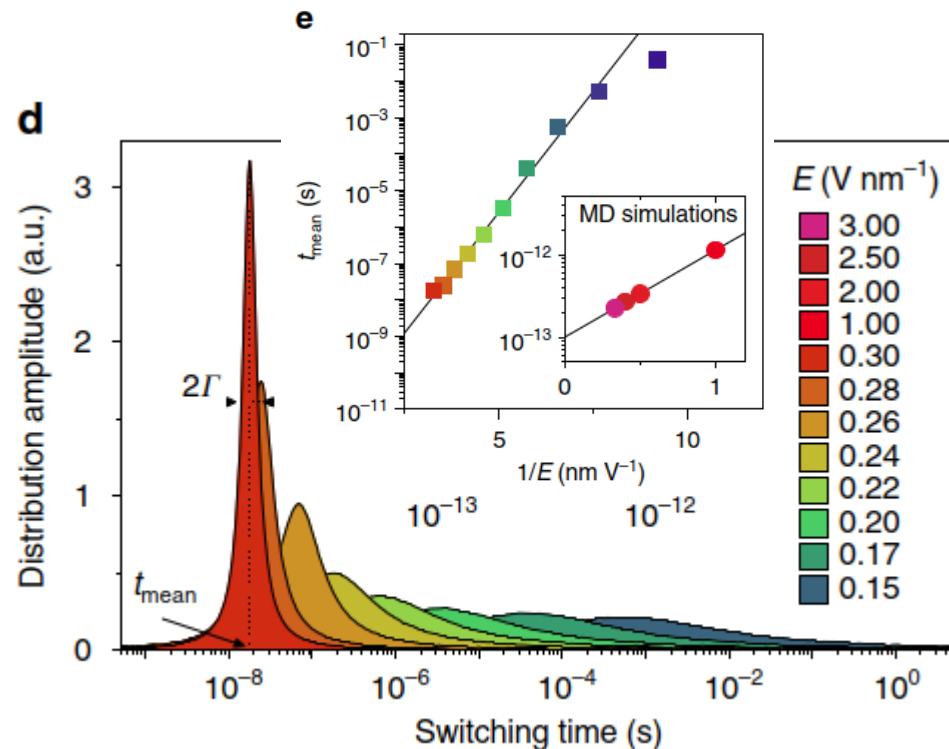
$$G = (1 - S)G_{\text{on}} + SG_{\text{off}}$$

where S is fraction of area with reversed polarity

Domain switching time

- Lorentzian distribution of $\log(t_{\text{mean}}(V))$
 - Lower $E \rightarrow$ longer time until switch

$$S_{\pm}(t, V) = \frac{1}{2} \mp \frac{1}{\pi} \arctan \frac{\log(t_{\text{mean}}(V)) - \log(t)}{\Gamma(V)}$$

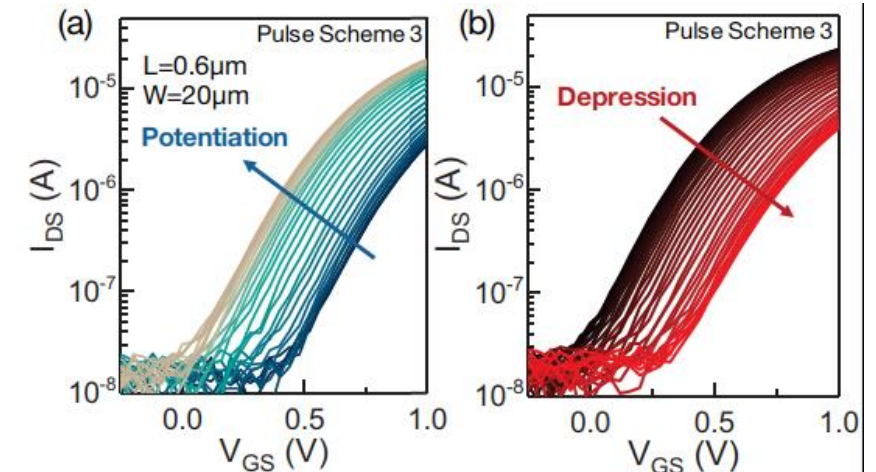
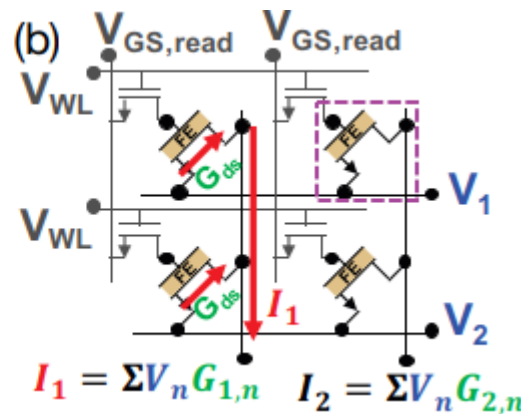
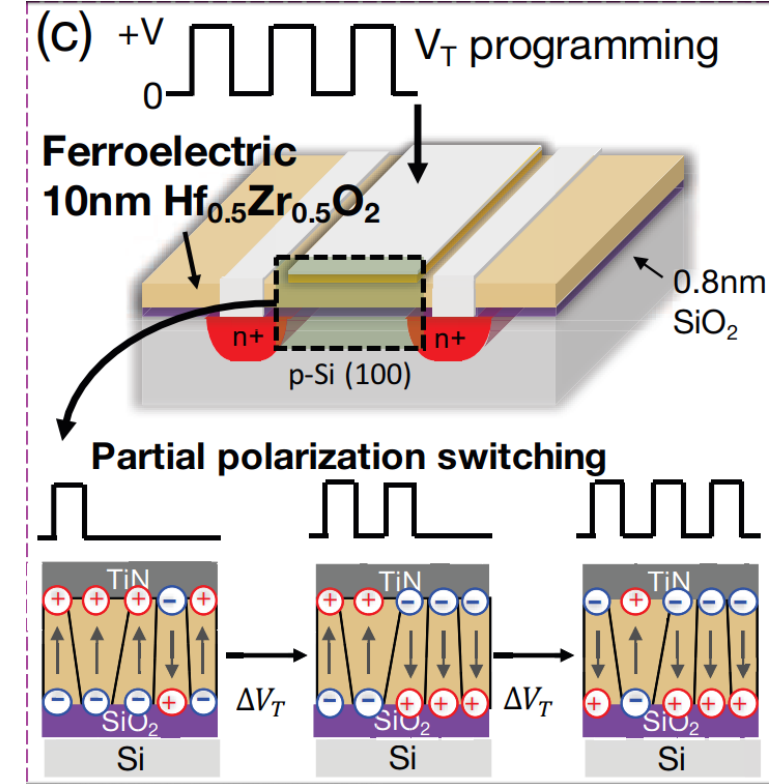
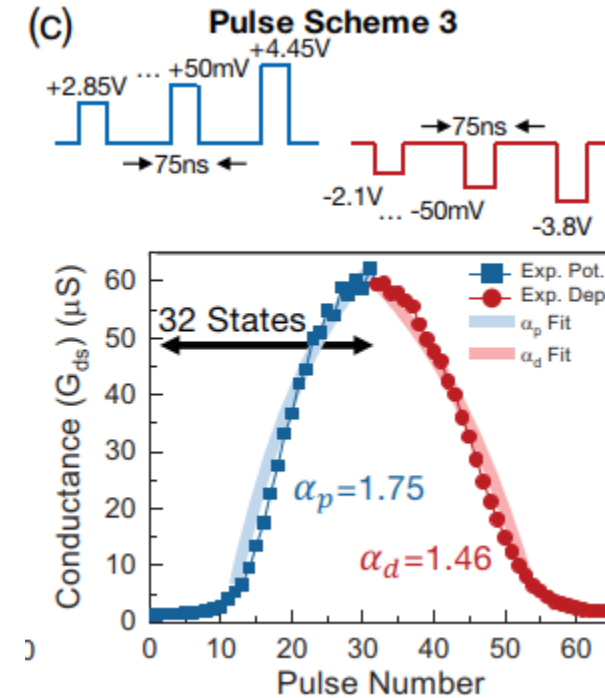
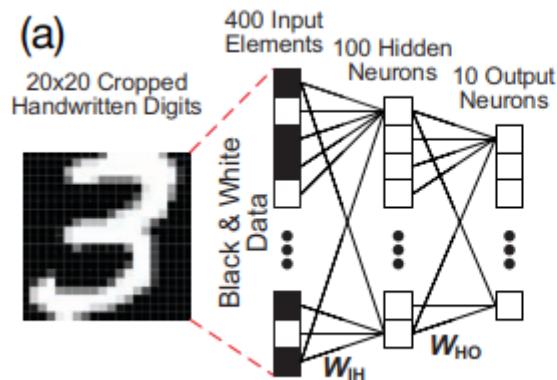


Ferroelectrics as storage

	DRAM	3DNAND	RRAM	PCM	STT-MRAM	Ferro
Nonvolatile	No	Yes	Yes	Yes	Yes	Yes(?)
Speed (ns)	10	10^4	< 5 ns	10 ns	< 5 ns	< 5 ns
Energy use (pJ/write)	0.1	1	0.1-1	>1	< 0.2 pJ	0.01 (!)
Endurance (cycles)	10^{16}	10^5	10^6 - 10^7	10^9	$>10^{15}$	10^5 - 10^{12}
Multilevel?	No	Yes	3-6 bit	4 bit	No	Yes(?)
Scalability	$6\text{-}8F^2$	3D!	3D!	3D!	$6F^2$	$4\text{-}6F^2$, 3D
Other	Destructive Read	High Voltage	Abrupt SET	R drifts	Scaling limited by needed current	Depolarization a challenge No multilevel when scaled?

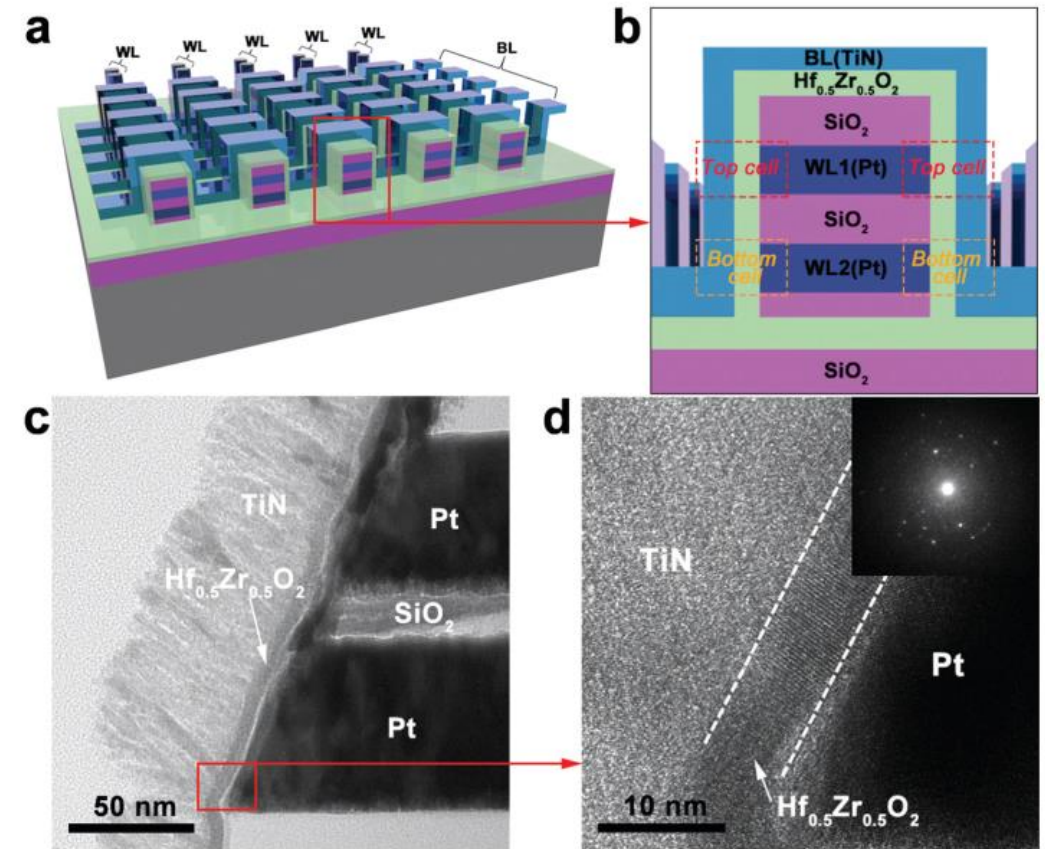
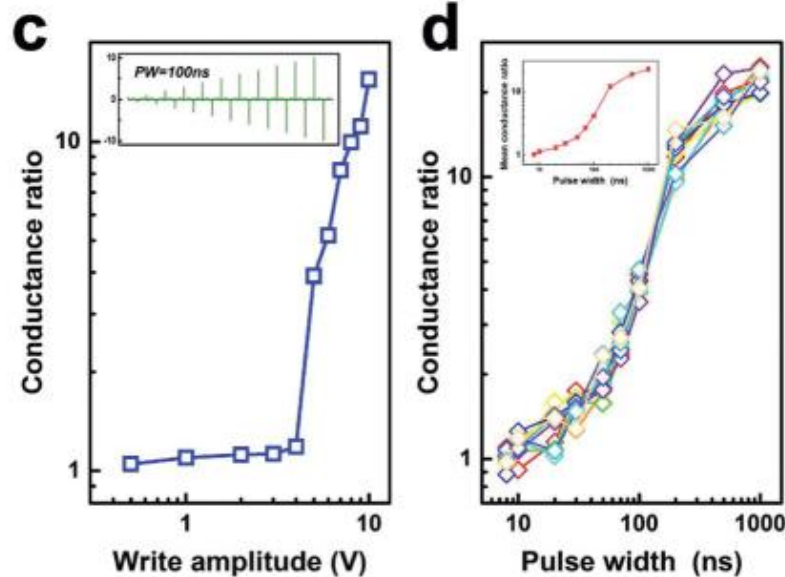
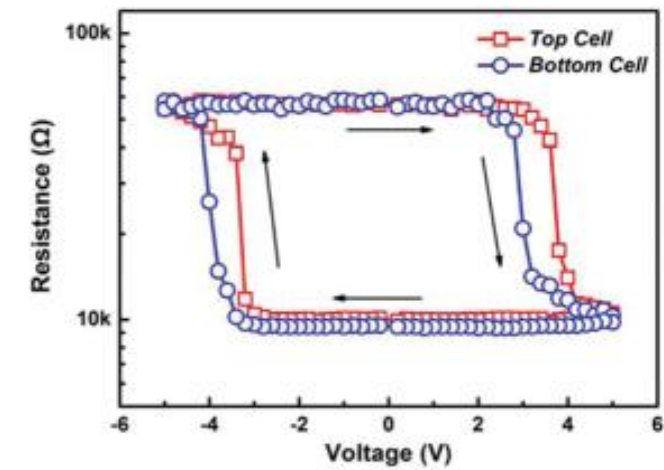
FeFET synapse

- Based on partial polarization switching
- Pulse scheme with varying amplitude used \rightarrow symmetric LTP/LTD
- $R_{\text{off}}/R_{\text{on}} \sim 45$, “5 bit” precision
- Tested with peripherals on MNIST numbers \rightarrow 90% accuracy at 35 μW
 - 10x area saving, > 30x less leakage power comp. with SRAM



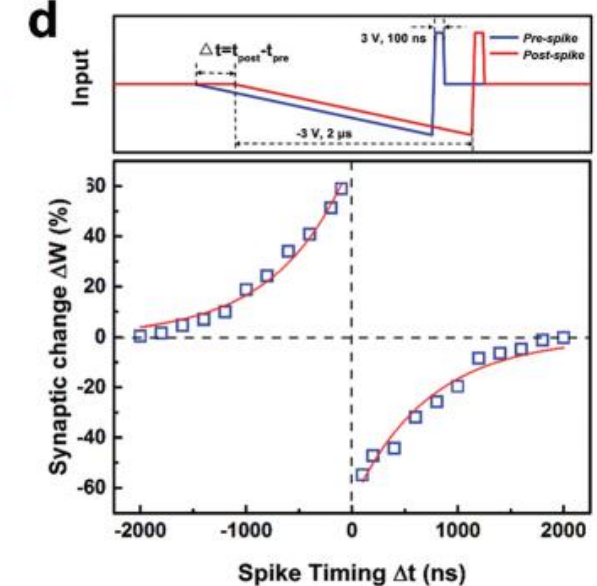
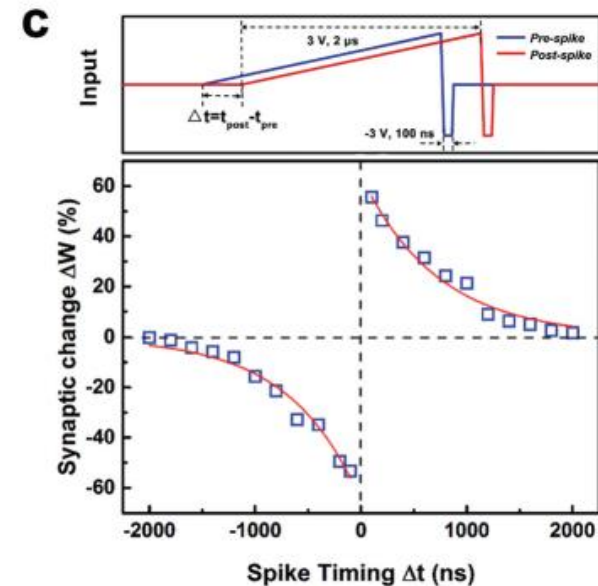
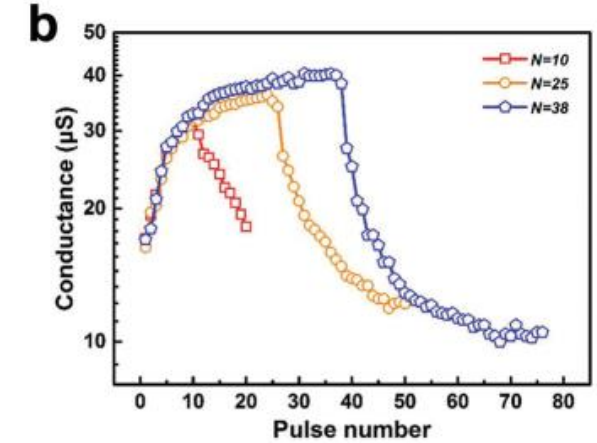
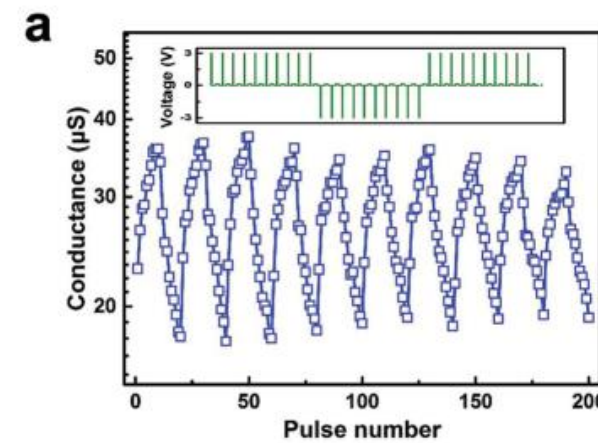
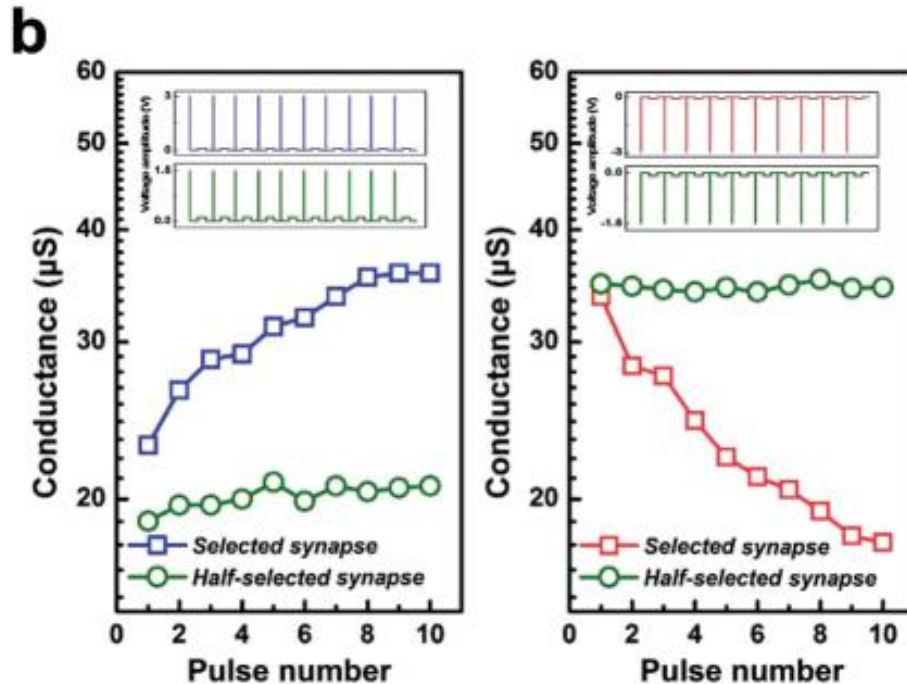
FTJ synapses

- 3D stacked FTJs implemented with HZO ferroelectric
- Control of resistance state by V_{write} and t_{write}
 - Exponential change...



Weight change in FTJ

- LTP and LTD possible, 1.8 pJ/spike ($2.5 \mu\text{m}^2$)
- Rather non-linear behaviour, more linear if not using full range
- STDP functionality is viable
- Selector-free operation is possible $\rightarrow 4F^2$



Summary

- Ferroelectricity → purely electronic effect (robust)
 - Promise of extreme energy efficiency: < 10 fJ/bit
- Three types of memories
 - FeRAM (stable but not scalable, destructive read)
 - FeFET (drop-in tech, challenging retention)
 - FTJ (new, two-terminal)
- FeFET and FTJ promising for synapse devices